

III-Nitride Nanowires for Solid-State Lighting

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Sandia MESA Facility



Sandia Albuquerque

Lighting is a large fraction of energy consumption and is low efficiency



Efficiencies of energy technologies in buildings:

Heating:	70 - 80%
Elect. motors:	85 - 95%
Fluorescent:	~17%
Incandescent:	~4%

Lighting is one of the most inefficient building energy technologies → opportunity!

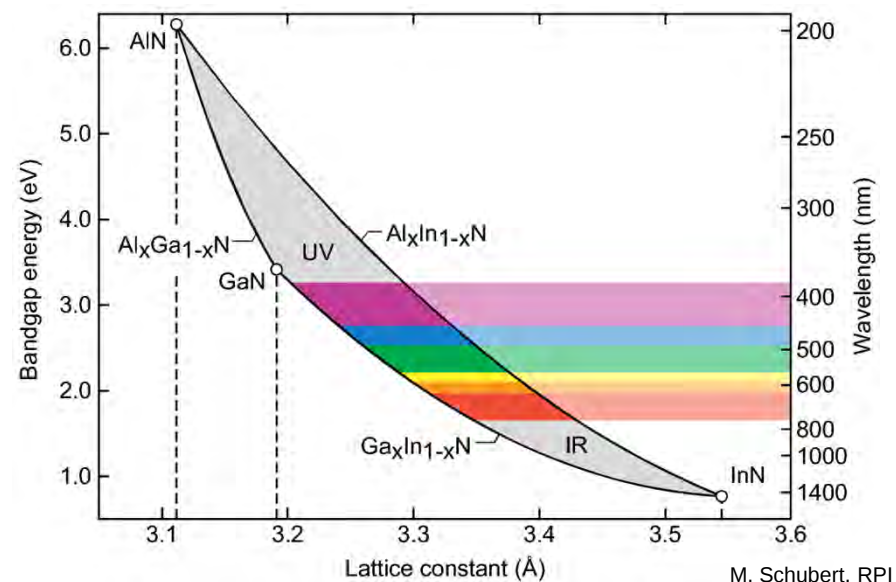
- ~22% of US electricity consumption is for general illumination (~1/15 world's energy, \$330B in 2005)
- Achieving 50% efficient lighting would have tremendous global impact:

US DOE target: 50%
"Ultra-efficient" SSL: $\geq 70\%$

- decrease electricity consumed by lighting by $> 50\%$
- decrease total electricity consumption by 10%

Foundation of SSL: III-Nitride (AlGaInN) Semiconductors

- **Direct RT bandgaps: ~0.7-6.2 eV**
- Solid alloy system (tuneable bandgaps)
- High breakdown field, mobility, thermal conductivity, melting temperature
- Radiation resistant and chemically inert
- InGaN covers entire visible & bulk of solar spectrum (PV material?)



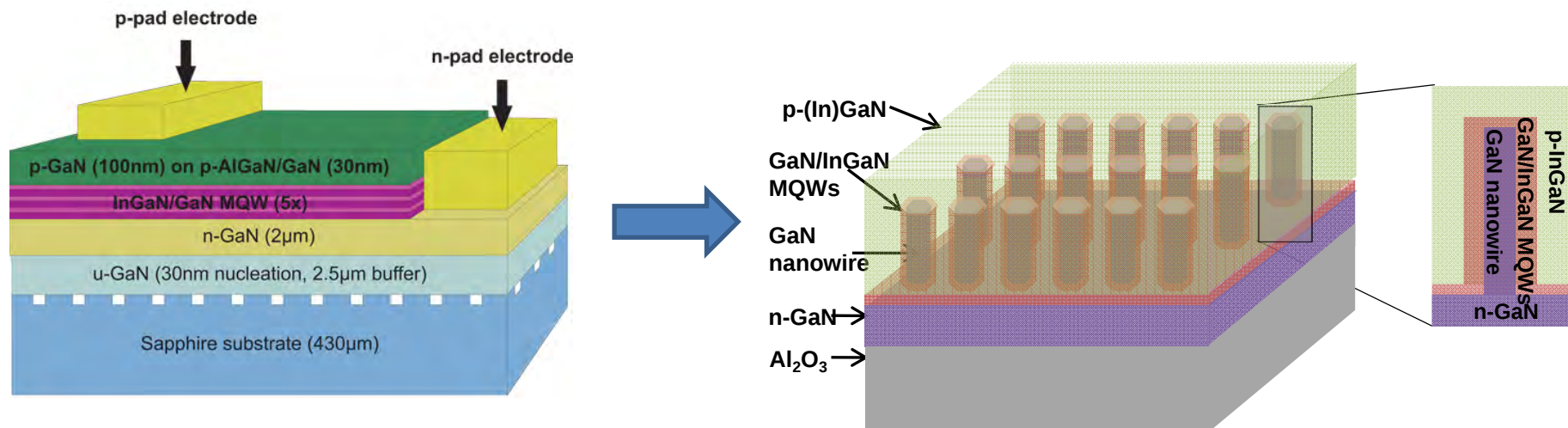
- *Used in LEDs, blue laser diodes, high power transistors, HEMTs*



Nitronex GaN power transistor



Why III-nitride (AlGaInN) nanowires for SSL?



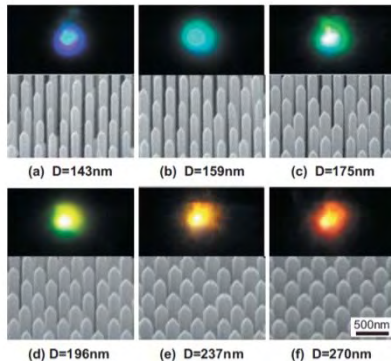
Y.S. Lin and J. A. Yeh, Appl. Phys. Express, vol4, p092103, 2011

Why III-nitride (AlGaInN) nanowires for SSL?

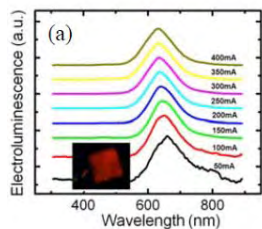
Advantages due to enhanced strain accommodation in nanowires

elastic strain relaxation at surface

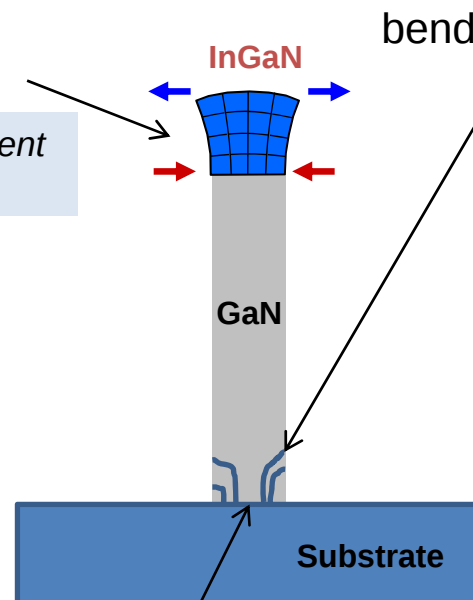
benefit: heterostructures with high In content (e.g. green-yellow-red gap)



Sekiguchi et al., APL **96**, 231104 (2010) – Sophia U.

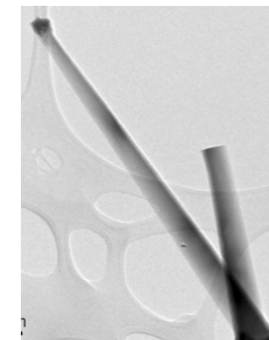


Nguyen et al., PTL IEEE **24**, 321 (2012) - McGill

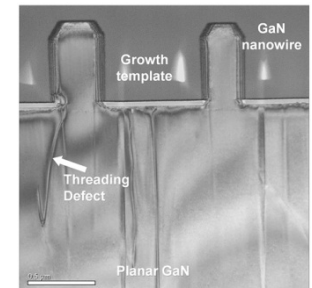


bending of dislocations (TDs) toward surface

benefit: reduced TDs, higher IQE



VLS-grown TD-free GaN NWs - Sandia

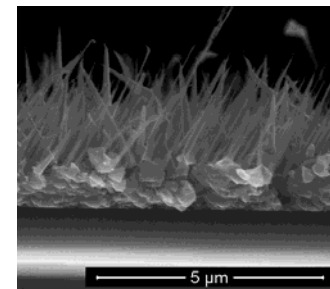


Hersee et al., J. Mat. Res. **17**, 2293 (2011) - UNM

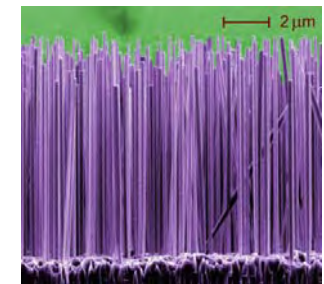
Bending & termination of TDs at nanowire base

small interfacial area

benefit: can grow on cheaper, lattice mismatched substrates; integration with Si devices



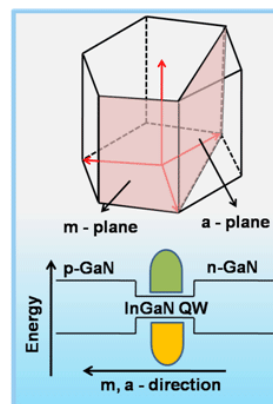
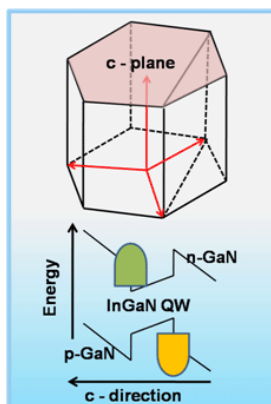
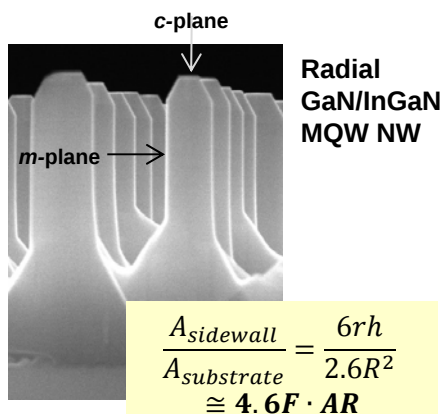
GaN NWs on tungsten foil - Sandia



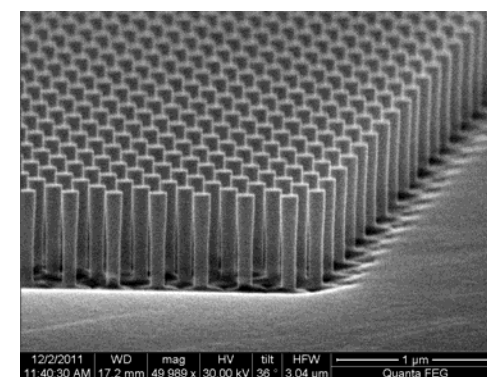
GaN NWs on Si - NIST

Why III-nitride (AlGaInN) nanowires for SSL?

Size, geometry	Nanowire attribute	Benefit
	Vertical 3D device integration (radial)	High surface/device area = lower cost;
	Non-polar, semi-polar facets	Reduced polarization effects (IQE)
	2D arrangements, e.g. photonic crystals	Enhanced/controlled light extraction, wavelength tuning, rad. recombination (IQE)
	Nanolasers	Lower threshold lasers; reduced eff. droop
	Discrete; (and all of the above)	Scientific test system



Non - polar direction GaN thin film growth → higher quantum efficiency



GaN NW photonic crystal

Worldwide GaN-based nanowire SSL-related research

North America

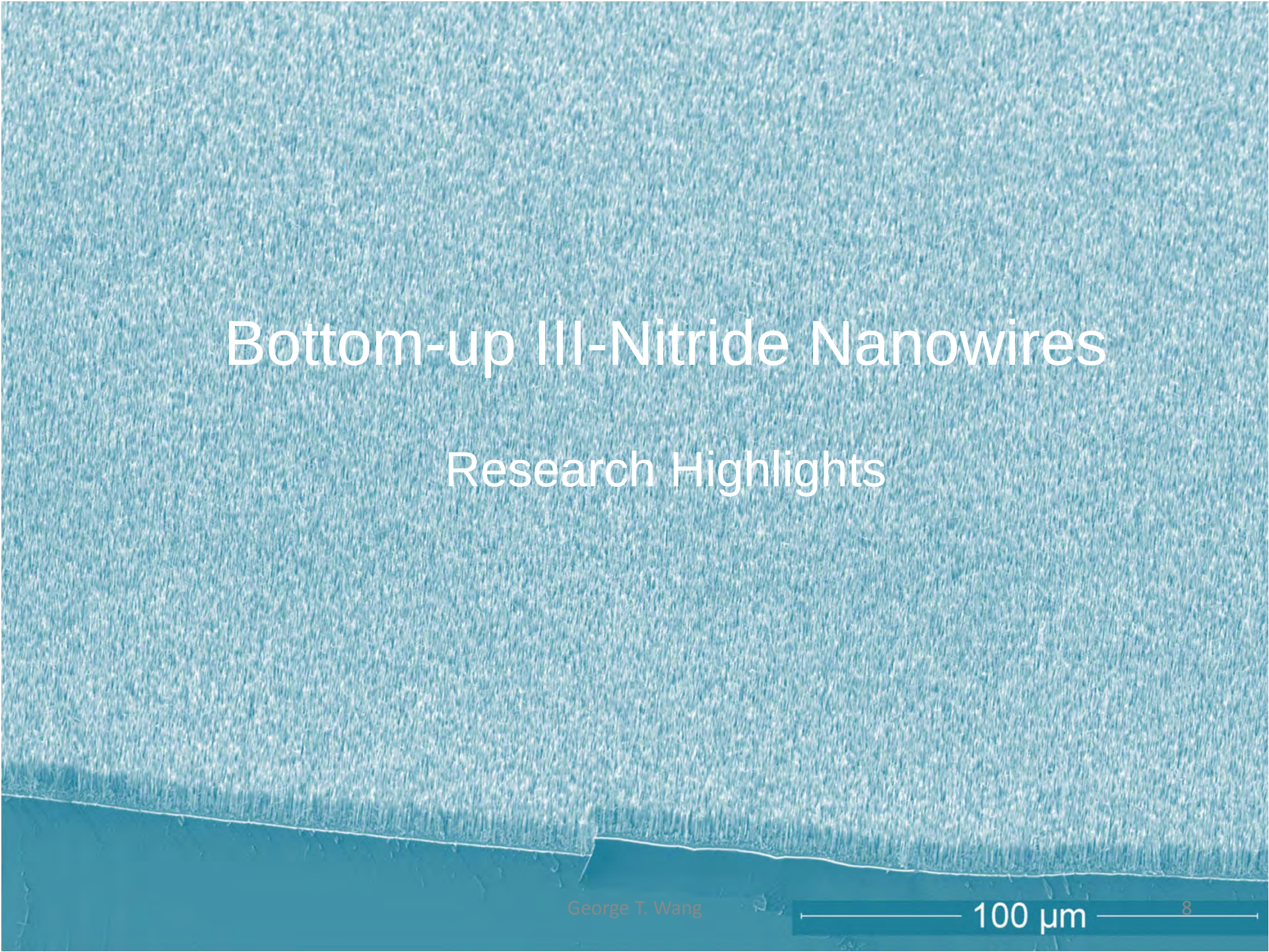


Europe



Asia



The background of the slide is a scanning electron micrograph (SEM) showing a dense, uniform forest of vertical nanowires. The nanowires are thin and extend from a flat substrate at the bottom to the top of the frame. The overall color is a monochromatic blue/teal.

Bottom-up III-Nitride Nanowires

Research Highlights

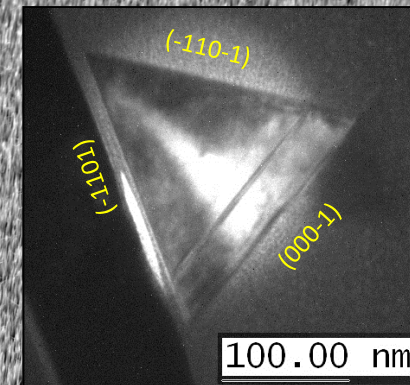
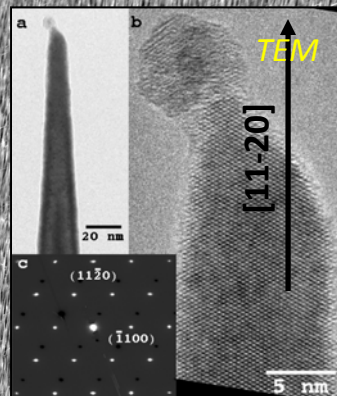
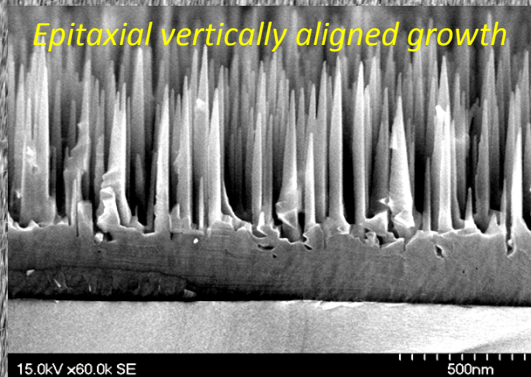
George T. Wang

100 μm

8



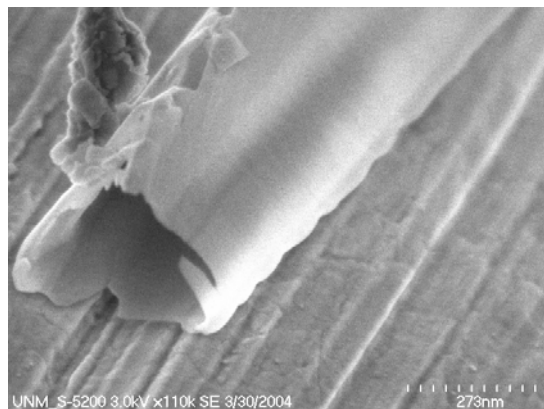
“Bottom Up” aligned GaN nanowire growth



- Nanowires grown by Ni-catalyzed MOVPE/MOCVD (VLS)
- Highly-aligned vertical growth over large areas (2" r-sapphire wafer)
- Controllable densities as high as ~ 150 nanowires μm^{-2}
 - Q. Li, G. T. Wang, *Appl. Phys. Lett.* 93, 043119 (2008)
 - Q. Li, J. R. Creighton, G.T. Wang. *J. Crys. Growth* 310 3706-3709 (2008)
- Primary [11-20] growth orientation ($\perp$ to (11-20) α -plane)
- Triangular faceted -- (000-1) and equiv. (-1101) and (-110-1)
- TEM: Single crystal, dislocation free; c-plane stacking faults
 - G. T. Wang et al., *Nanotechnology* 17 5773-5780 (2006)

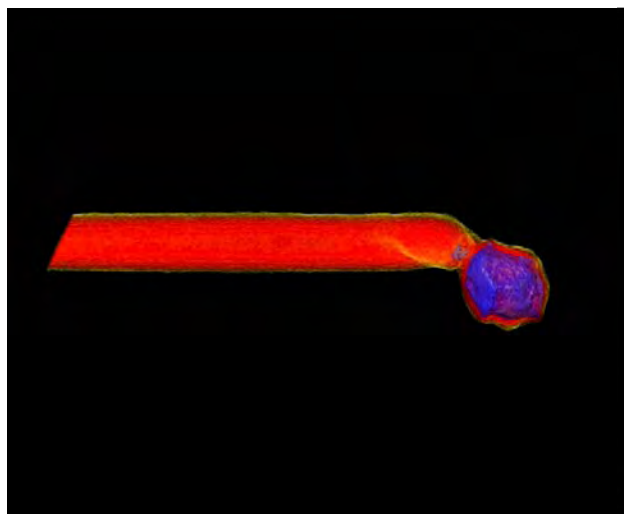


Radial heterostructure nanowire growth



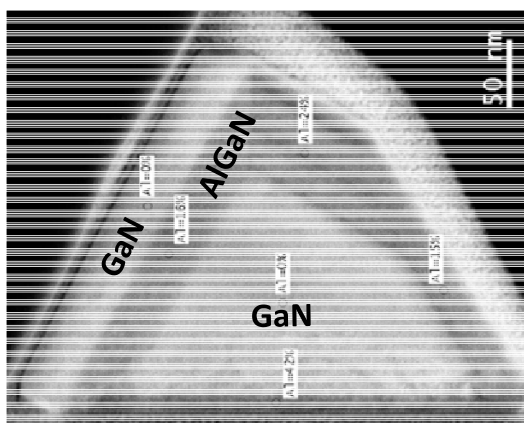
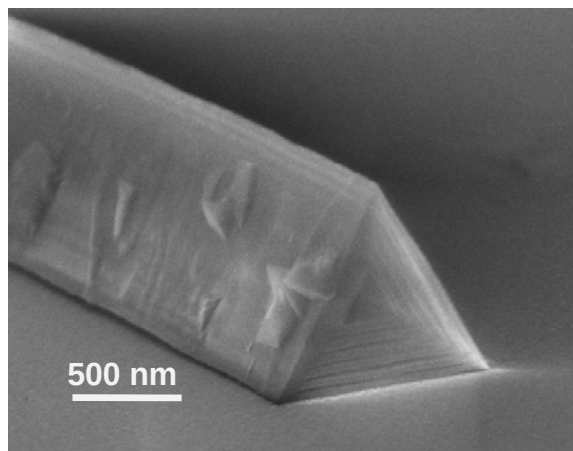
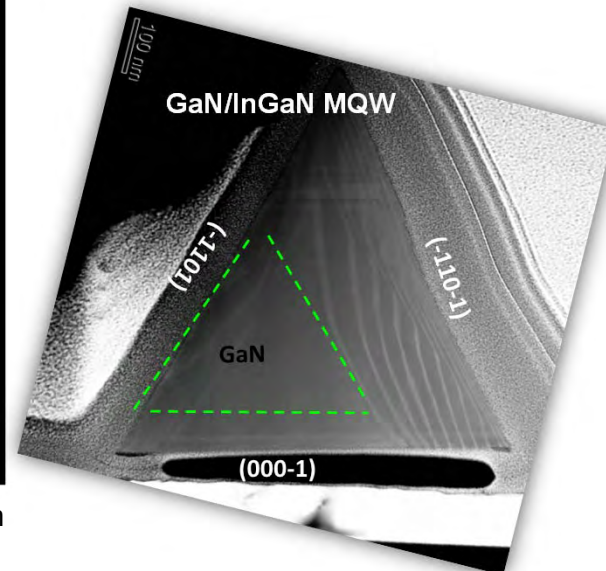
G. Stan et al., *Nanotechnology*, **20**, 2009

AlN Nanotubes

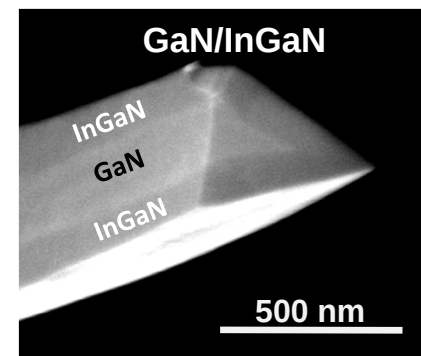


GaN/AlN NW

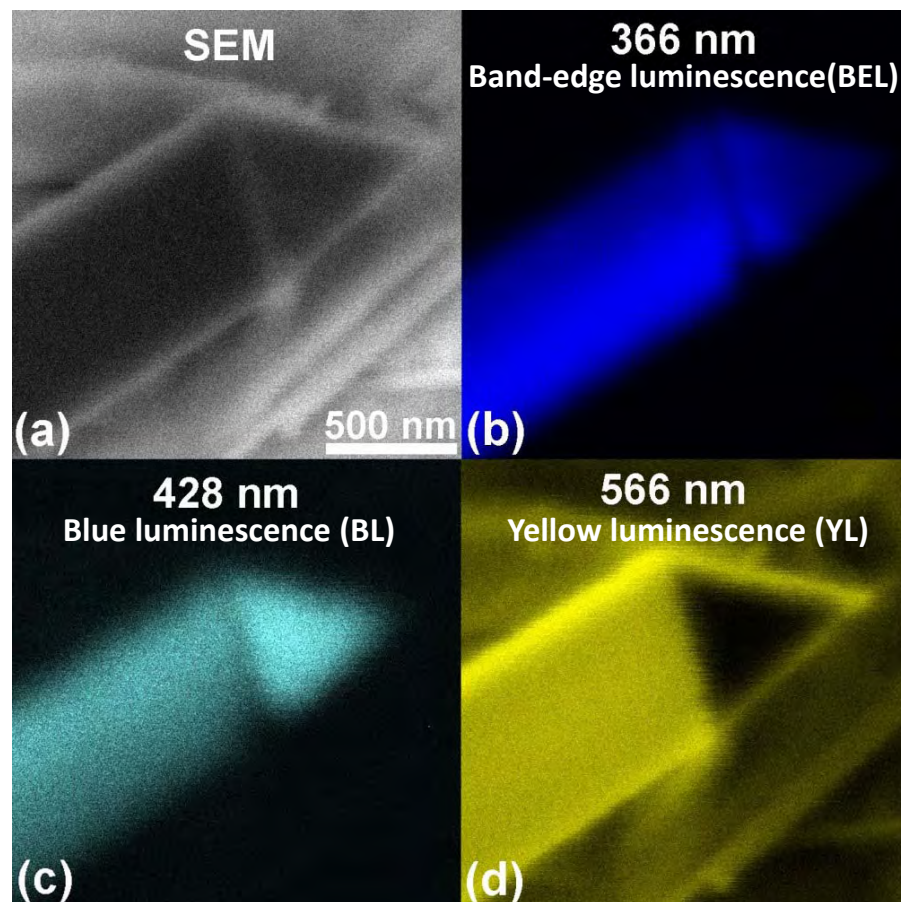
I. Arslan



GaN/AlGaIn/GaN
Double heterostructure



Spatial distribution of luminescence in GaN NWs



- Band-edge luminescence (BEL) at ~ 366 nm and defect-related blue luminescence (BL) at ~ 428 nm observed in NW core/bulk
- **Defect-related yellow luminescence (YL) exhibits strong surface component** -- associated with surface states or concentrated near surface region
- YL in GaN attributed to many possible sources (C, O impurities, Ga vacancies, etc.)
- Isolated Ga vacancies have low diffusion barrier (~ 1.5 eV) & may migrate toward surface during growth
- BL linked to $V_{\text{Ga}}\text{-O}_{\text{N}}$ ($D \sim 2.2$ eV), less mobile

Nanoscale Cathodoluminescence (CL) imaging: Cross-section GaN NW

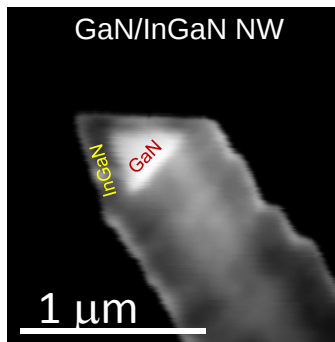
Q. Li, G. T. Wang, *Nano Lett.*, 2010, 10 (5), 1554

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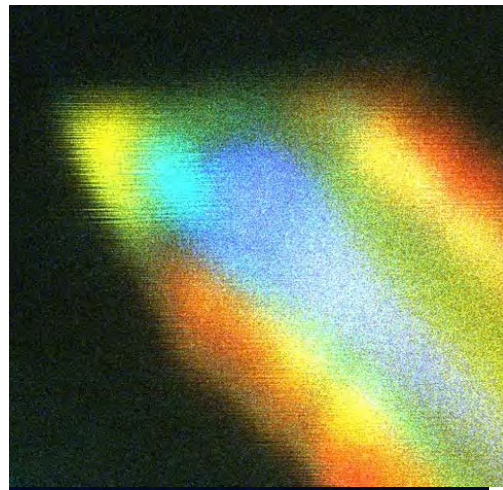


Core-shell NWs – A good platform for high In InGaN?

- **Issue: Strain limits In incorporation in InGaN thin films (green-yellow-red gap)**
- Radial core-shell NWs: much higher active region area than axial NW or planar heterostructures

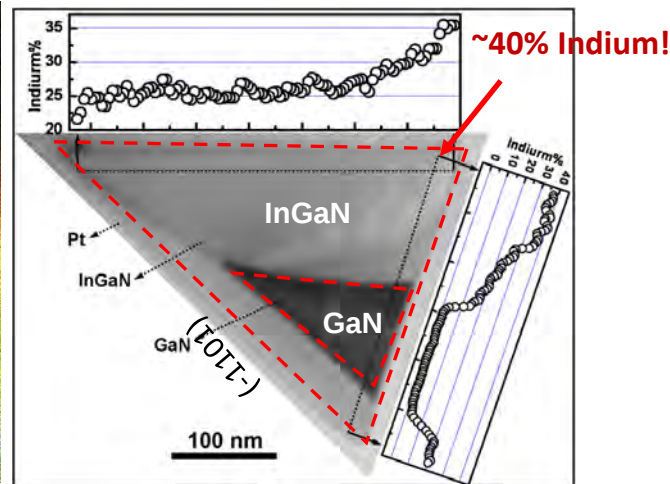


GaN core – 900 °C, 10 min.
InGaN shell – 760 °C, 60 min.



CL shows strong multicolor emission up into the IR!

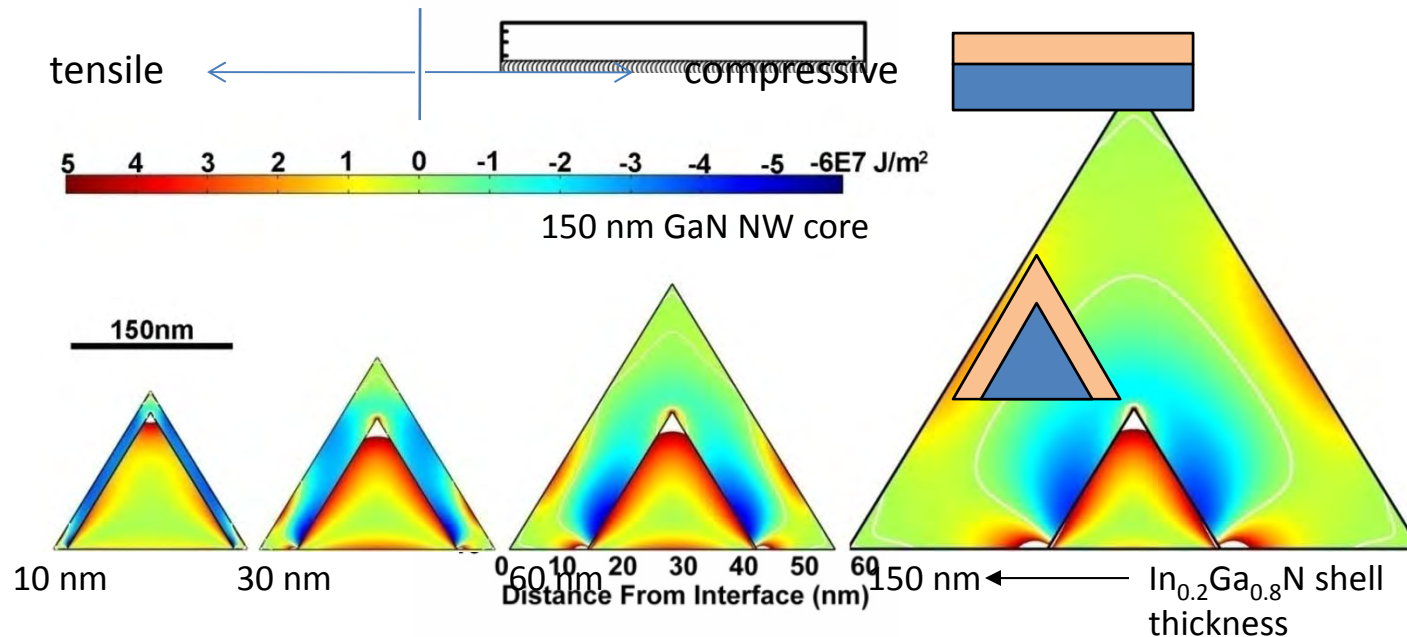
- **high In incorporation with high material quality**
- nonuniform In composition?



STEM/EDS shows In distribution, **highest at surface/corners**



Reduced strain in nanowires allows higher In incorporation

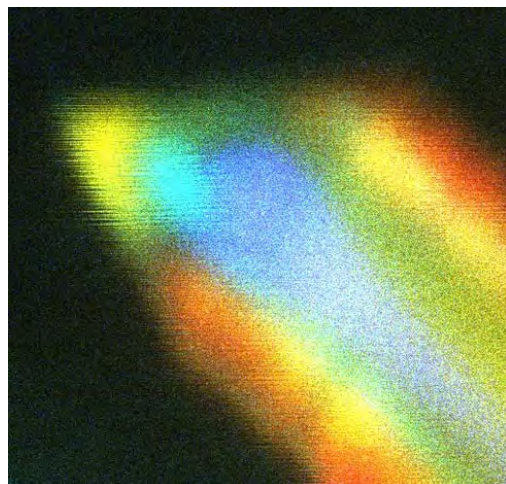
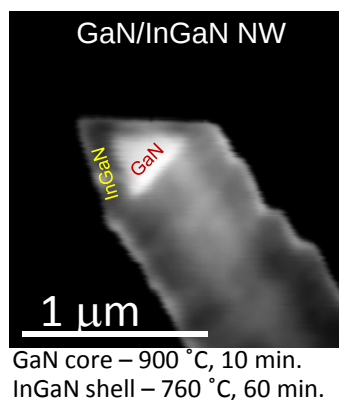


- Strain lower for GaN/InGaN nanowire than for GaN/InGaN thin film
- Compressive strain decreases away from GaN/InGaN interface, lowest in corners

Q. M. Li, G. T. Wang, "Appl. Phys. Lett.", 97, 181107 2010.

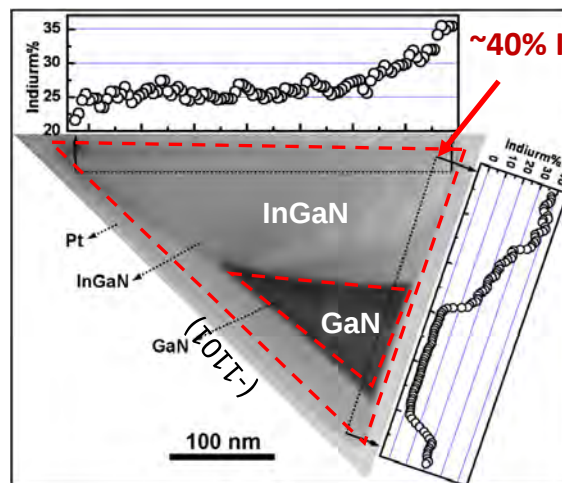
Strain-dependent In incorporation in GaN/InGaN core-shell NWs

- **Issue: Strain limits In incorporation in InGaN thin films (green-yellow-red gap)**
- Radial core-shell NWs: much higher active region area than axial NW or planar heterostructures

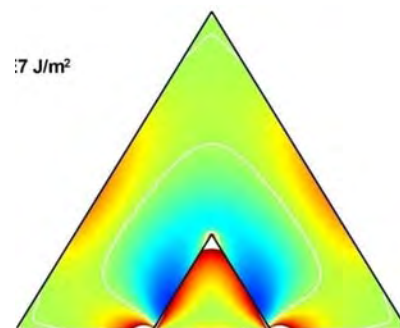


CL shows strong multicolor emission up into the IR!

- **high In incorporation with high material quality**
- nonuniform In composition?



STEM/EDS shows In distribution, **highest at surface/corners**



2D FEA: highest In regions correlated w/lowest compressive strain regions

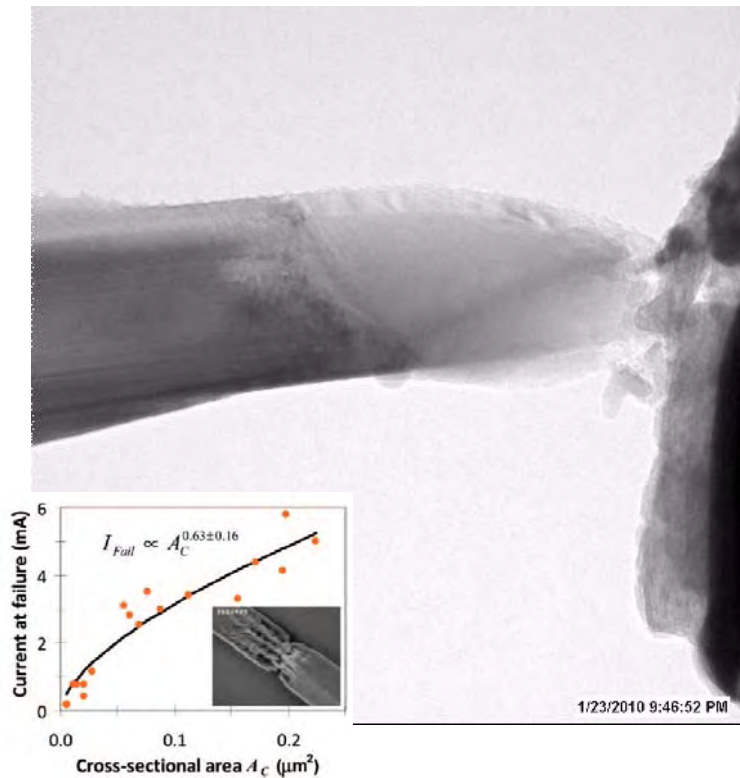
Q. M. Li, G. T. Wang,
“Appl. Phys. Lett., 97,
181107 2010.

Radial InGaN/GaN nanowires promising for addressing green-yellow-red gap



In-situ TEM studies

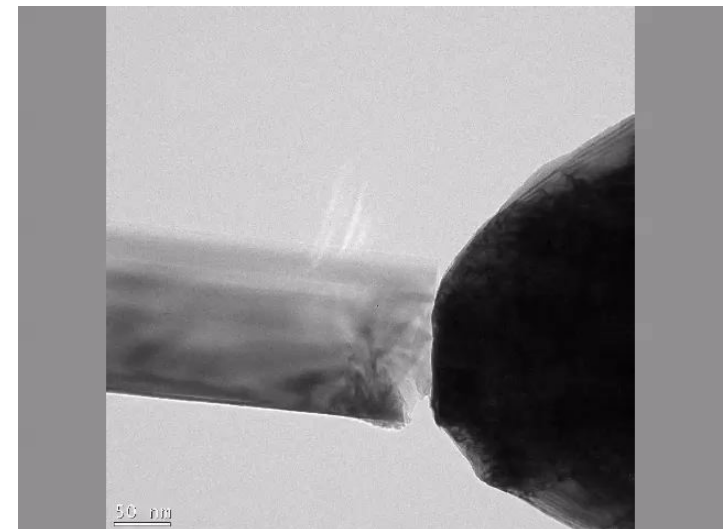
GaN NW decomposition via Joule heating
(relevant for NW devices)



NW breakdown at 60V, 20 μA
(avg. breakdown $I \sim 3000 \text{ kW/cm}^2$)

T. Westover, R. Jones, J. Y. Huang, G. Wang, E. Lai, A. A. Talin, *Nano Lett.*, **9**, 257 (2009).

Local plastic deformation of GaN NW
(relevant for NW devices)



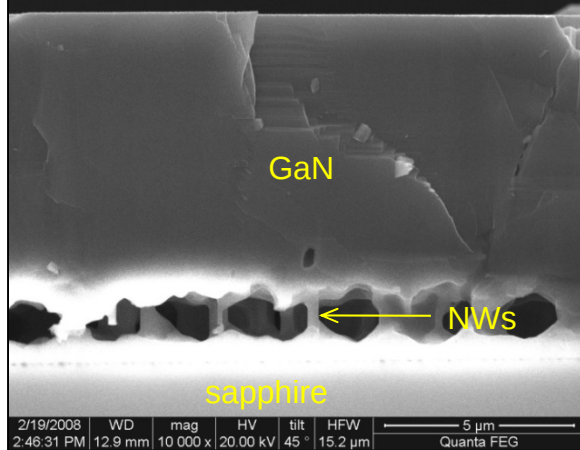
- Dislocation-free NW shows significant surface plastic deformation
- Mediated by dislocation nucleation & pile up, grain boundary sliding

J. Y. Huang, H. Zheng, S. X. Mao, Q. Li, and G. T. Wang, *Nano Lett.*, **11** (4), 1618 (2011).

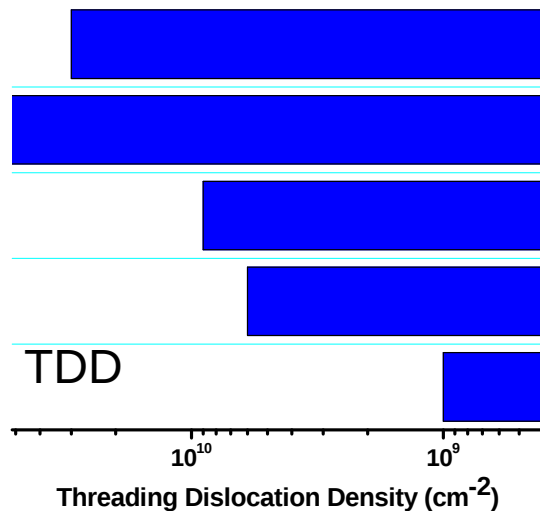
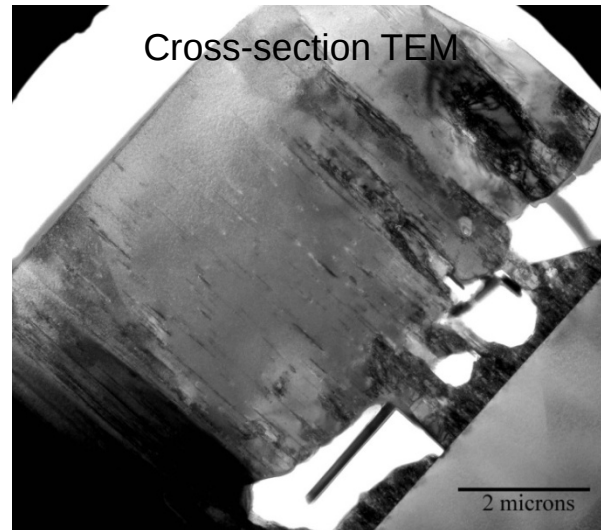
Nanowire-templated lateral epitaxial growth (NTLEG) of GaN

Inexpensive method to reduce dislocation density in GaN films growth on lattice mismatched substrates

Nanowire array growth: 780 °C 3 min.
Lateral growth step 1: 900 °C 15 min.
Lateral growth step 2: 1075 °C for 15 min.



Cross-section SEM



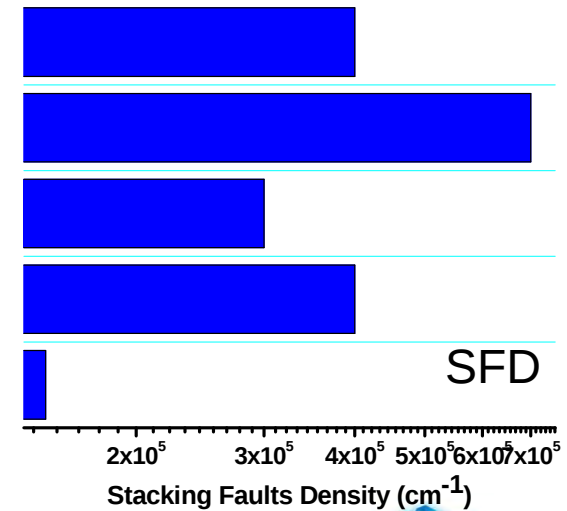
Craven et al., *APL* 81(2002), 469
(LT nucl. Layer)

Chakraborty et al. *APL* 89(2006), 041903
(LT nucl. Layer)

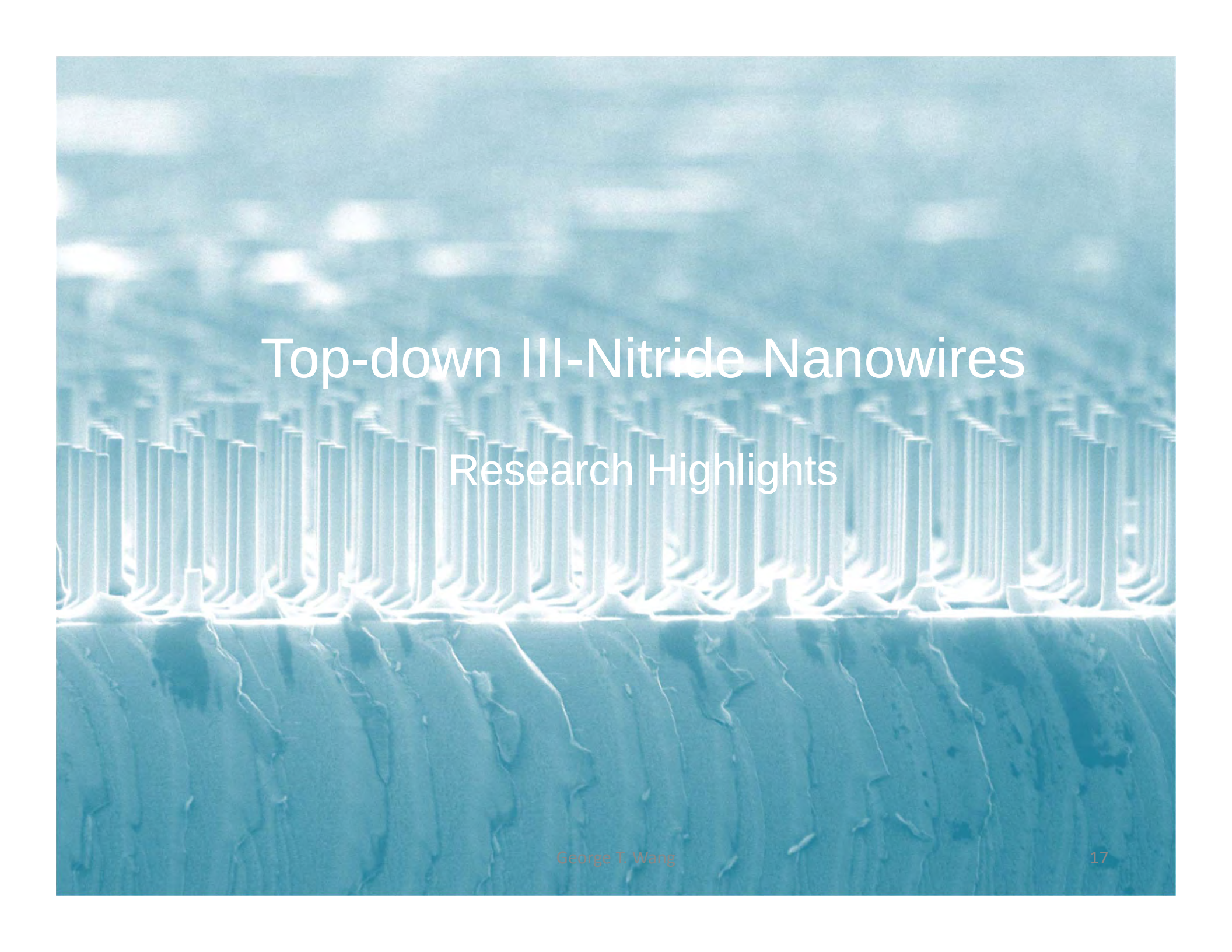
Chakraborty et al. *APL* 89(2006), 041903
(SiNx Nanomask)

Qian et al, *JAP* 106(2009), 123519
(HT AlN nucl. Layer and 3-step growth)

Li et al. *Adv. Mat.*, 21(2009), 2416
(NTLEG) THIS WORK



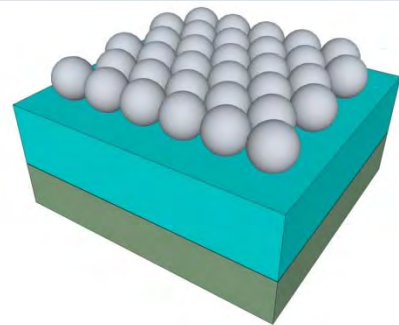
SFD

A scanning electron micrograph (SEM) showing a dense array of vertical, rectangular nanowires. The nanowires are arranged in a regular grid pattern and extend from a textured substrate. The image is rendered in a blue color scheme. The text "Top-down III-Nitride Nanowires" is overlaid in white, sans-serif font in the upper-middle section of the image.

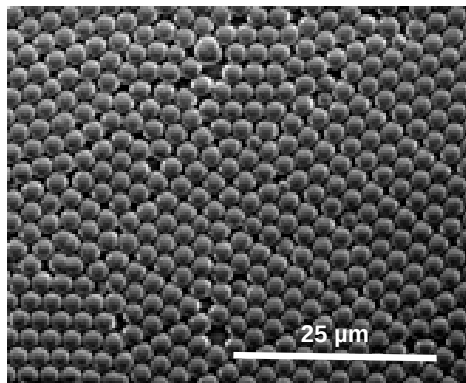
Top-down III-Nitride Nanowires

Research Highlights

New dry + wet top-down ordered nanowire fabrication process

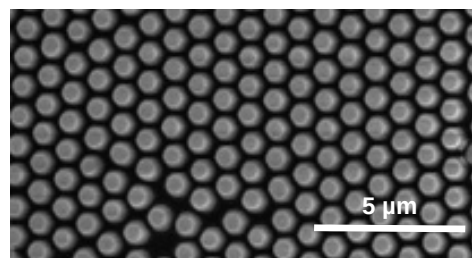
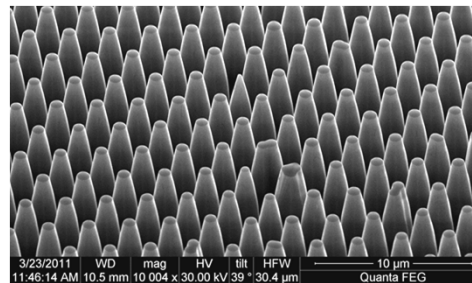
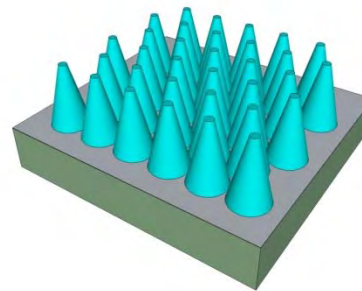


(0001) GaN on sapphire



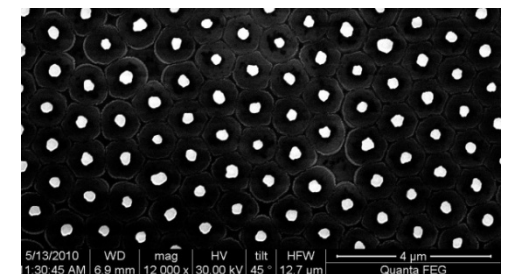
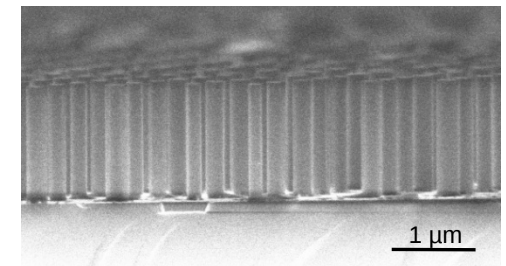
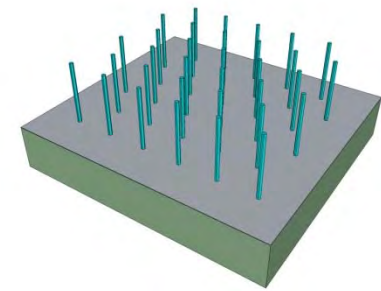
Q. Li, J. J. Figiel, G. T. Wang, Appl. Phys. Lett., **94**, 231105 (2009).

ICP etch



Plasma etch causes sidewall damage
C. Y. Wang et al., Opt. Expr. **16**, 10549–10556, 2008.
Tapered; no well-defined facets

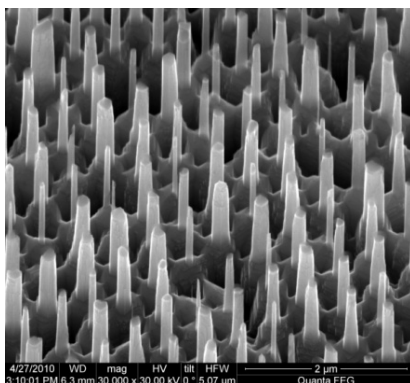
Selective wet
etch
(AZ-400K
developer)



Wet etch: straight sidewalls,
removes sidewall damage

Straight GaN nanowires with controllable geometries

0.5 μm sphere size



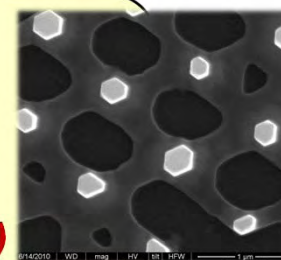
Wet etch rate negligible for top (Ga-polar) c-face & fast for [10-10], leads to hexagonal NWs with **straight & smooth** *m*-facets

Superior and independent control of:

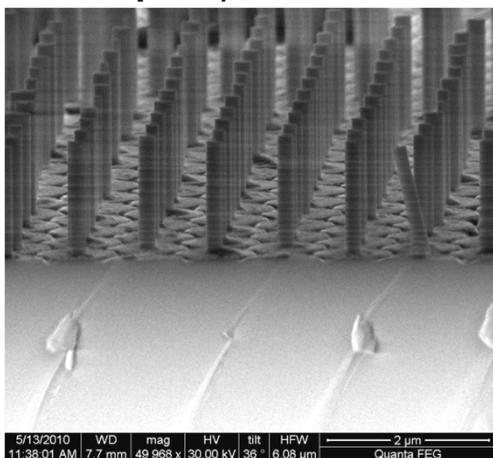
Height (dry etch depth)

Diameter (wet etch time)

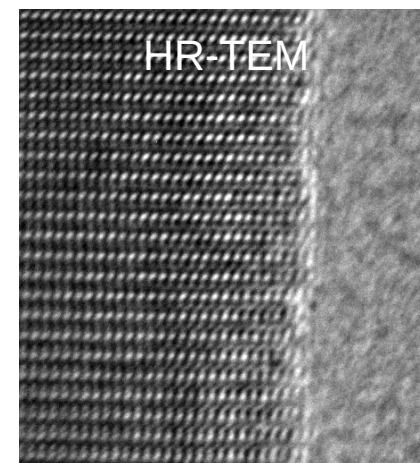
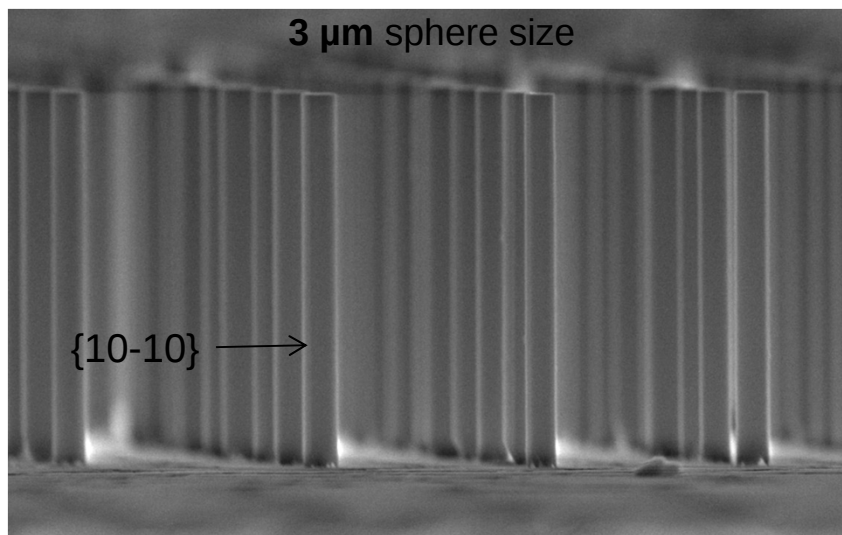
Pitch/arrangement (defined by masking template)



1 μm sphere size



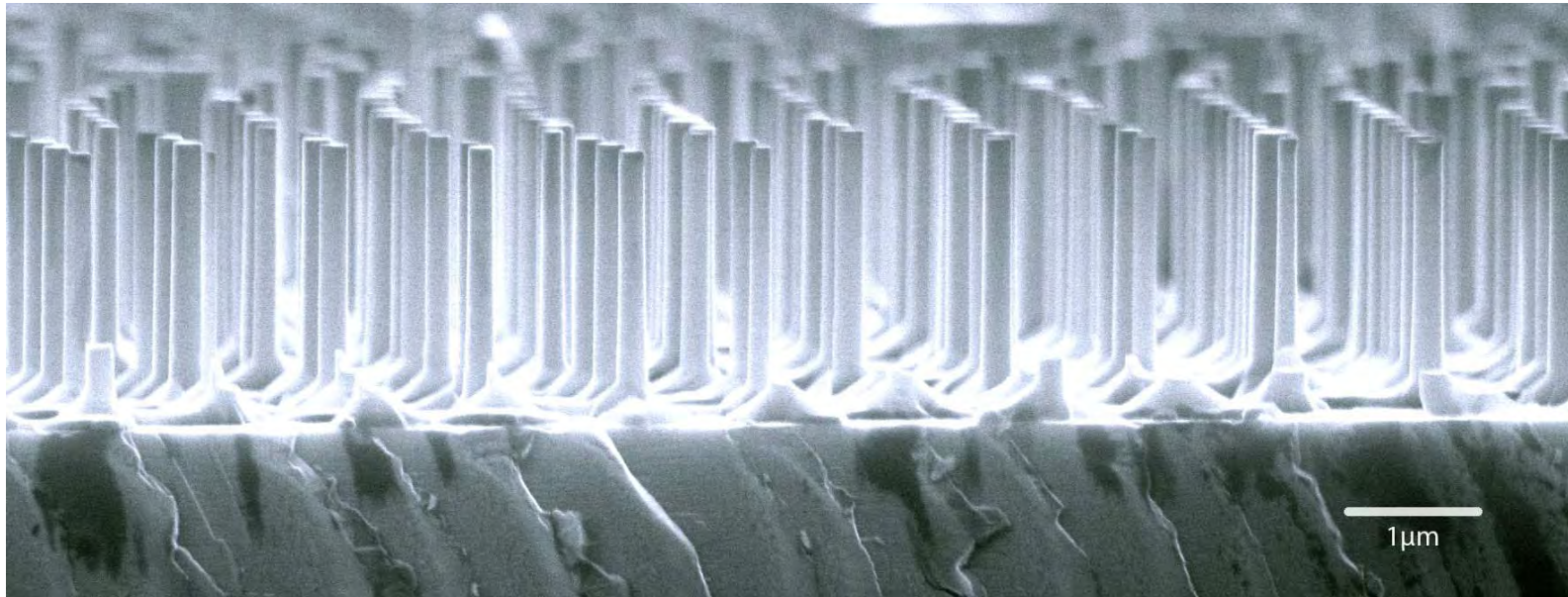
3 μm sphere size



Smooth sidewall created by wet etch



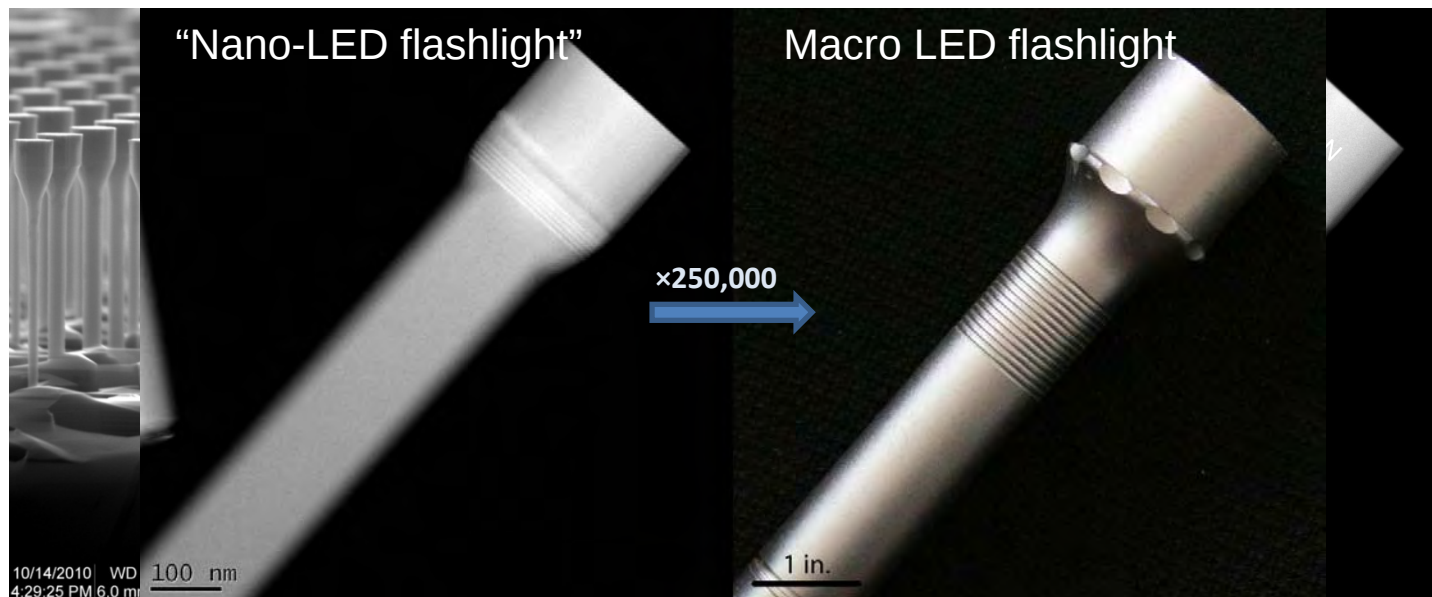
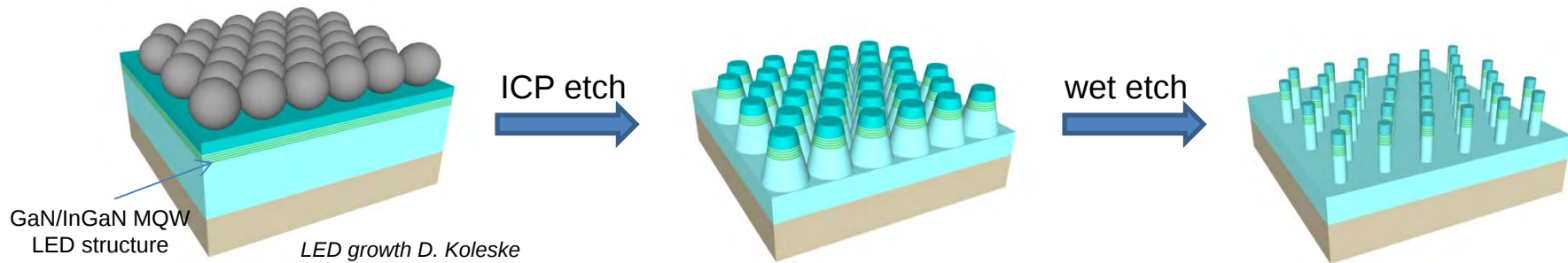
Advantages of new top-down nanowire fabrication method



- Wider range of growth conditions, material tunability (1D growth cndns not needed)
- Lower point defect densities (higher growth temperature)
- Ordered/periodic arrays (difficult with catalyst/VLS-based methods)
- Axial III-nitride nanowire heterostructures possible by MOCVD
- Better control of geometry (independent control over height, width, & pitch)
- Improved uniformity
- Easier vertical device integration (height uniformity, base GaN-layer)



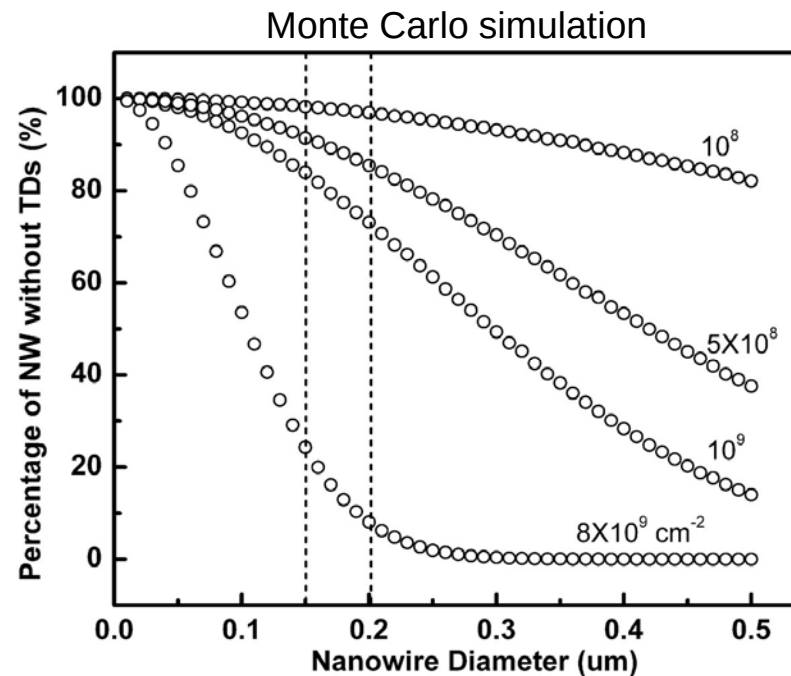
Axial GaN/InGaN nanowire LEDs



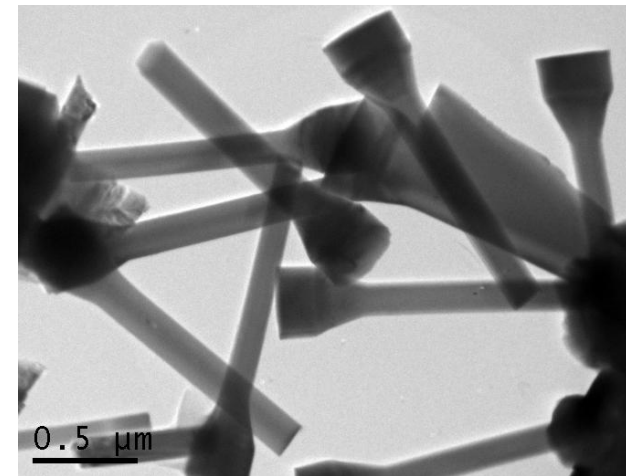
Q. Li et al.,
Optics Express **19**,
25528 (2011)



Top-down nanowire threading dislocations



Bright-field TEM



Nanowires etched from $\sim 5 \times 10^8 \text{ cm}^{-2}$ planar LED

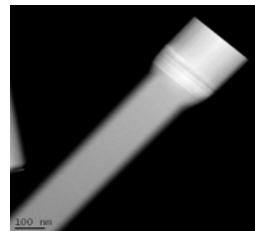
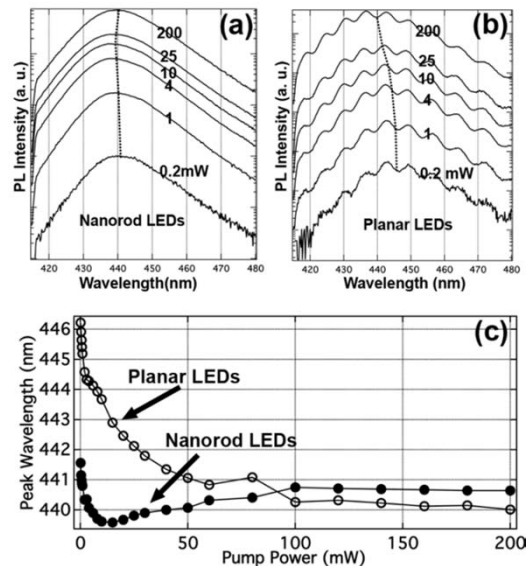
- Etched nanowires inherit the dislocation density of the parent film
- However, as the diameter approaches zero, the *fraction* of nanowires with one or more dislocations also approaches zero! [$\# \text{ TDs per rod} \sim (\text{TDD}) \times (A_{\text{cross-section}})$]
- *$\sim 94\%$ of nanowires $\sim 150 \text{ nm}$ in diameter from $\text{TDD} \sim 5 \times 10^8 \text{ cm}^{-2}$ film dislocation free!*

Optical performance – axial nanowire LEDs vs. planar LED

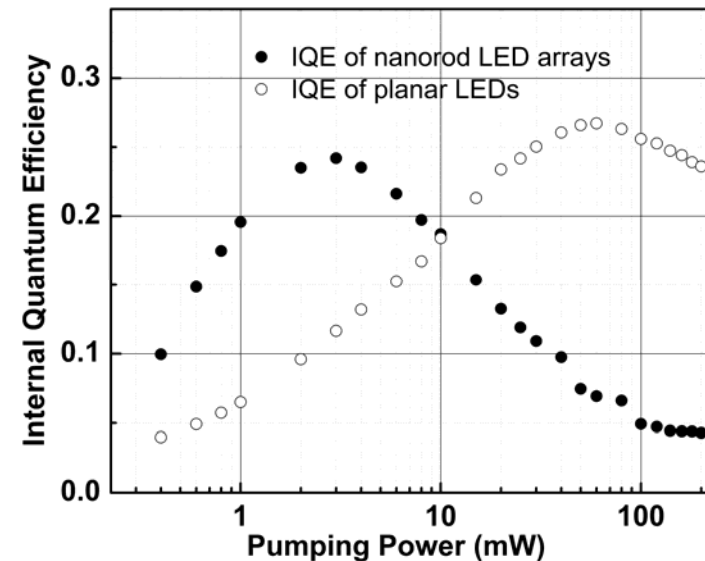
413 nm pump (InGaN selective)

PL, IQE measurement K. Westlake, M. Crawford

InGaN peak position vs pump power



IQE – nanowire vs Film



- XRD shows $\sim 16 \pm 4\%$ strain reduction in InGaN QWs in nanowire LEDs
XRD measurement courtesy Steve Lee
- Little wavelength shift at higher pump powers for nanowire LEDs (no/reduced QCSE)

- nanowire LED: comparable IQE to planar LED but peak IQE occurs at much lower pumping power (enhanced light absorption, heating)

Q. Li et al., *Optics Express* **19**, 25528 (2011)

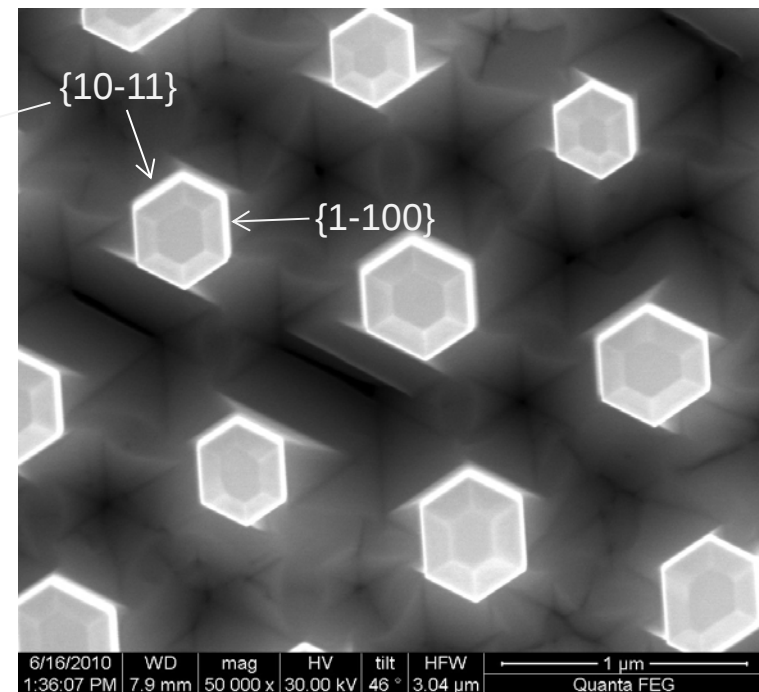
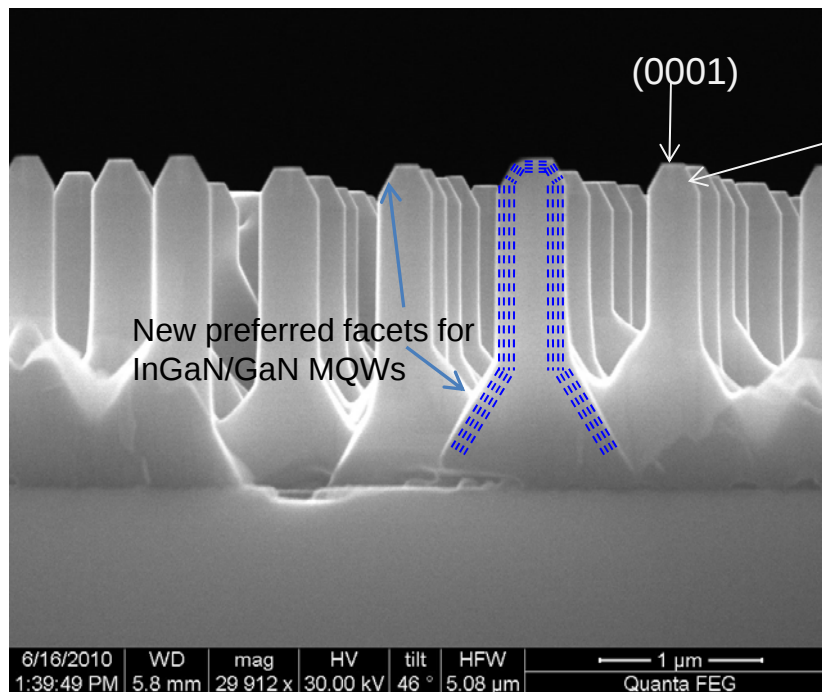


Radial core-shell InGaN/GaN MQWs on top-down NWs

Radial core-shell heterostructures

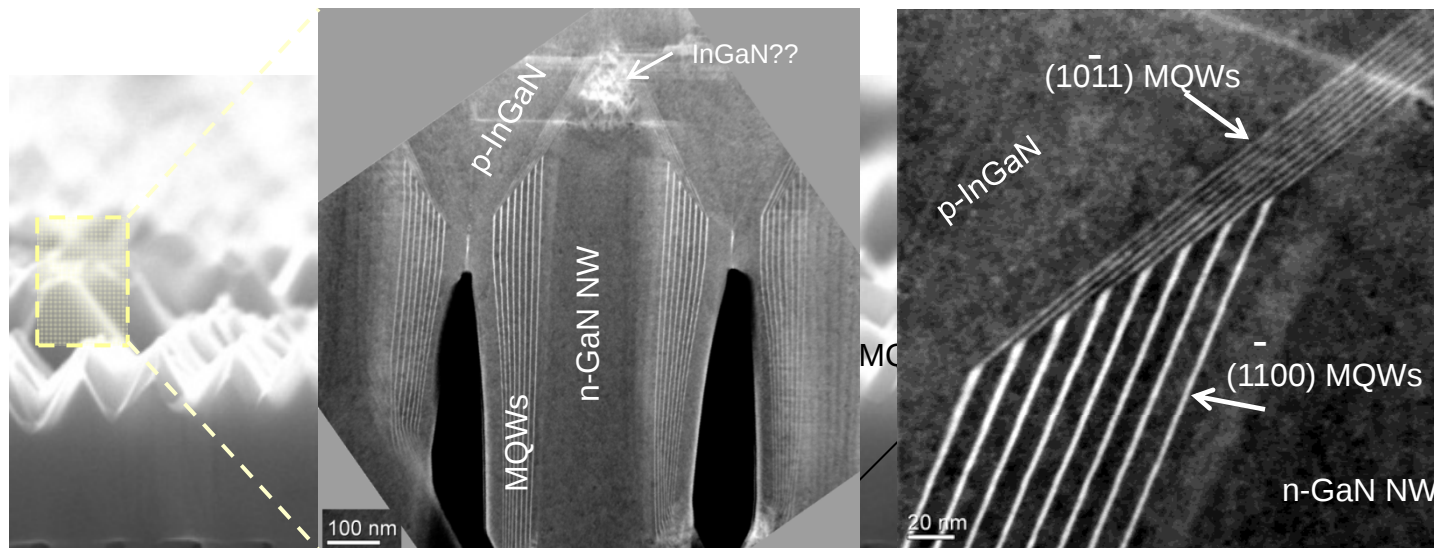
- Much higher active area than axial or planar structures
- Reduced strain InGaN growth for higher In incorporation

After 5-period MQW GaN/InGaN shell growth

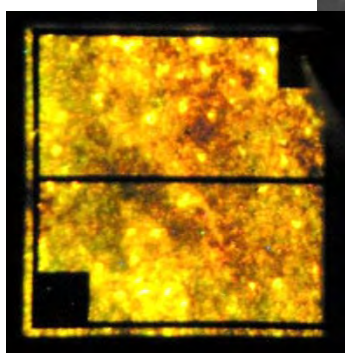


New semipolar facets form with InGaN/GaN MQW growth

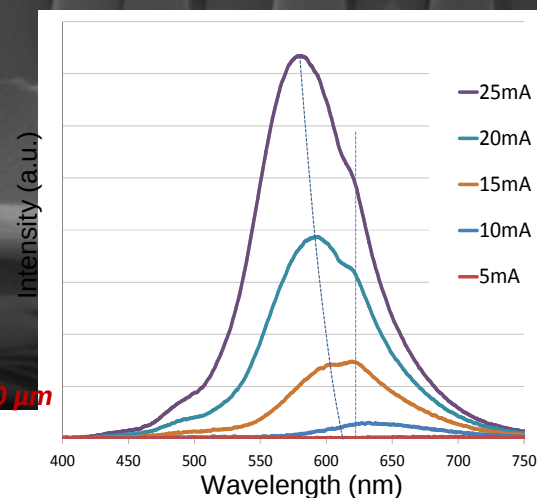
Highlight: Electrically injected core-shell nanowire based “3D” LED emitting at yellow-red wavelengths



J. Wierer et al., *Nanotechnology* 23 194007 (2012)



250×250 μm

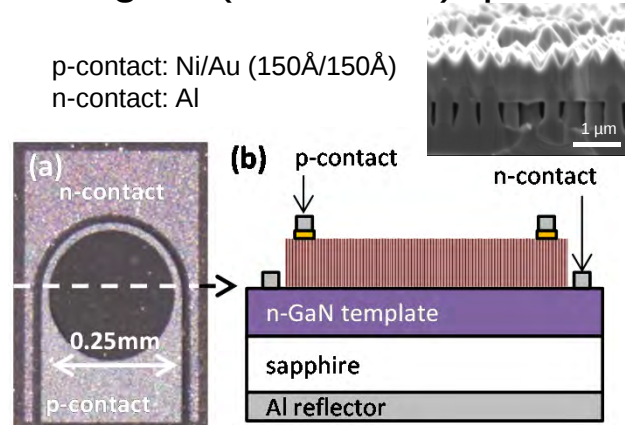


- Yellow-red electroluminescence!
- Two EL peaks:
 - 615 nm (const) red
 - 600-565 nm (shift) yellow

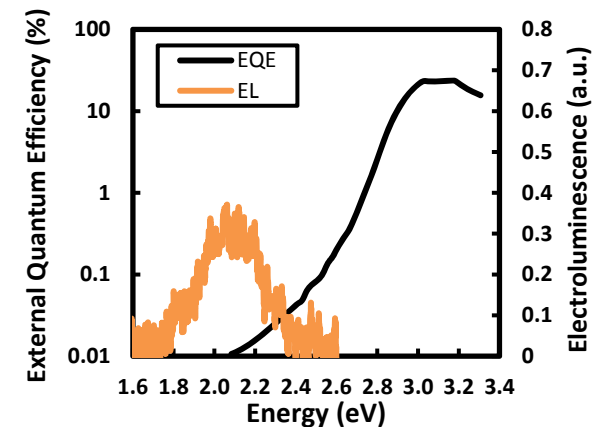
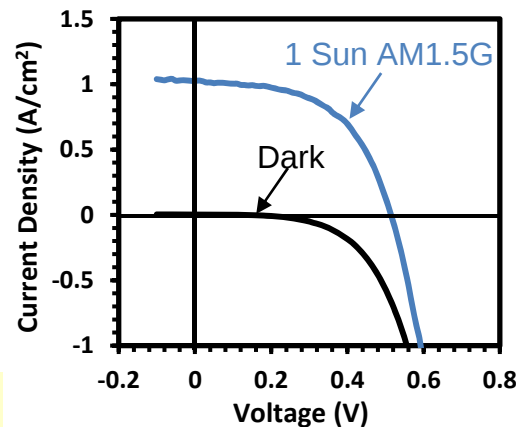


III-nitride nanowire arrayed solar cell

- III-nitride solar cells: InGaN bandgap (0.7-3.4 eV) covers solar spectrum; high rad. resistance
- Nanowire solar cells: increased light scattering/absorption, short carrier collection lengths (core-shell), potentially smaller bandgap cell (higher In content InGaN layers)



J. Wierer et al., *Nanotechnology* 23 194007 (2012)



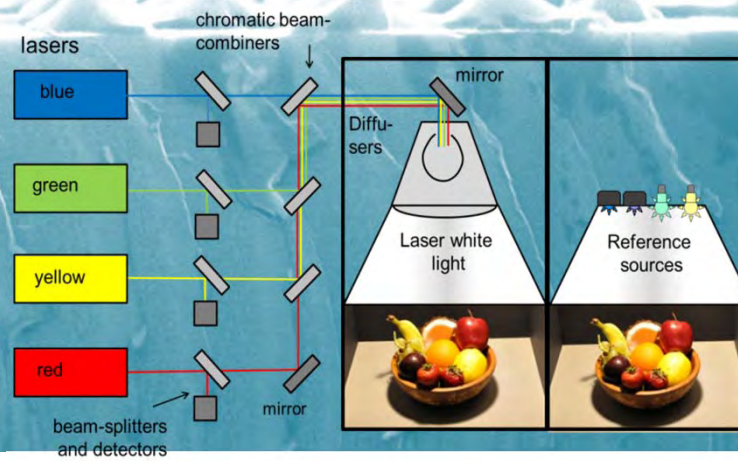
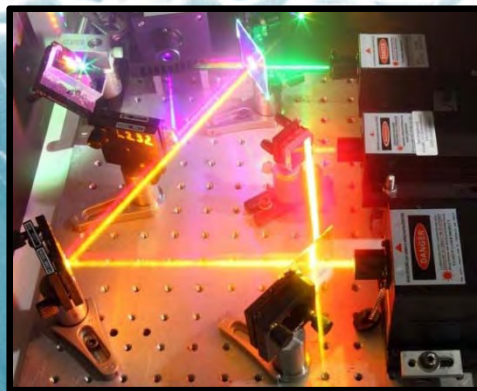
- *First vertically integrated III-nitride nanowire solar cell* Previous Work: Single III-nitride NW solar cell:
Dong, Y. et al., *Nano Lett.* 9 2183 (2009)
- Peak EQE ~23% at 3.0 eV; Photoresponse to 2.1 eV (590 nm), lowest bandgap reported for III-nitride solar cell; V_{OC} ~ 0.5 V; FF ~ 54%; Power conversion efficiency ~0.3% (shorting from defects in nanowire templates)



Nanowire Lasers

Why Nanowire Lasers?

- *Nanowire forms a freestanding, low loss optical cavity*
- *Compact and low power due to small mode volume*
- *Possibility of high efficiency lasers at green and yellow wavelengths*
- *Potential applications including electronic/optical integration, sensing, imaging, lithography, **lighting***
- *Lasers may circumvent droop problem in LEDs*



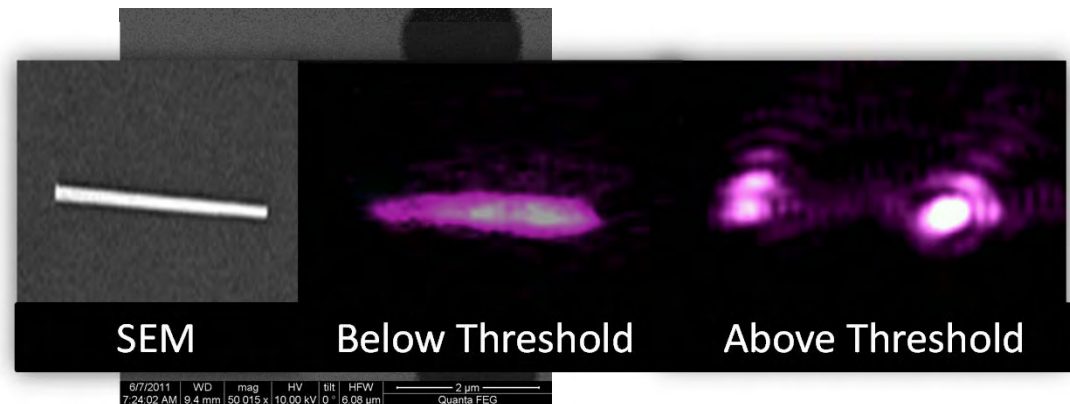
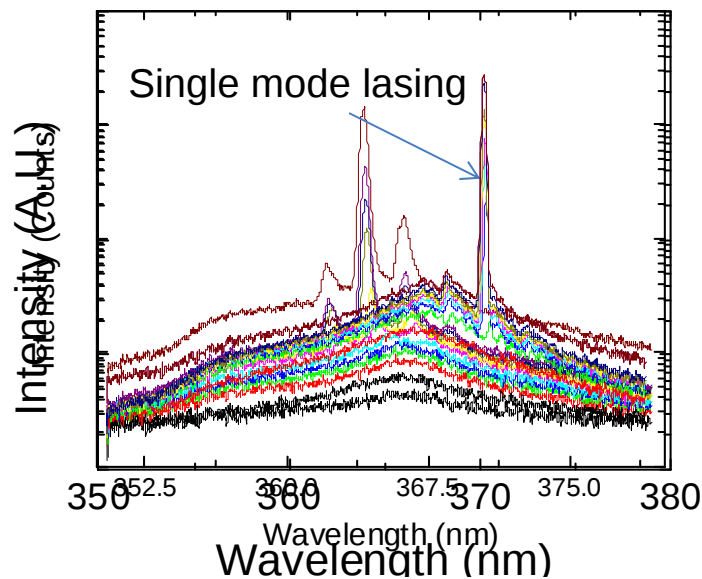
A. Neumann et al, *Optics Express*, **19**, A982-A990 (2011)

A scanning electron micrograph (SEM) showing a dense array of GaN nanowires. The nanowires are vertical, rectangular structures grown on a textured substrate. The image is in grayscale, with the nanowires appearing as bright, vertical lines against a darker, textured background.

Mode control (i.e. How to make a single-mode GaN nanowire laser)

Method 1: Single-mode GaN nanowire laser via geometry control

- Single-mode lasers are desirable (higher resolution, lower threshold & noise)



Nanowire dimensions: $\sim 130\text{ nm} \times 4.7\text{ }\mu\text{m}$
 Nanowire dimensions: $\sim 500\text{ nm} \times 4.7\text{ }\mu\text{m}$

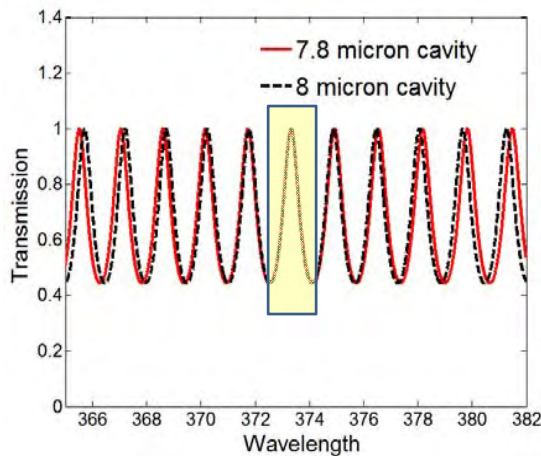
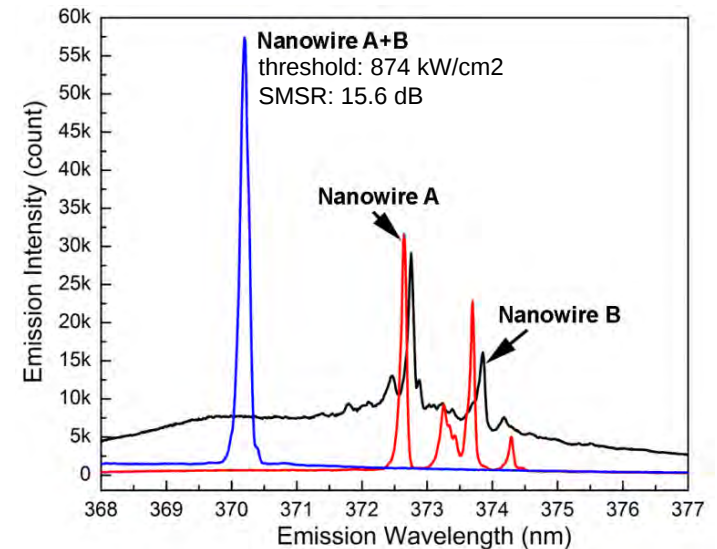
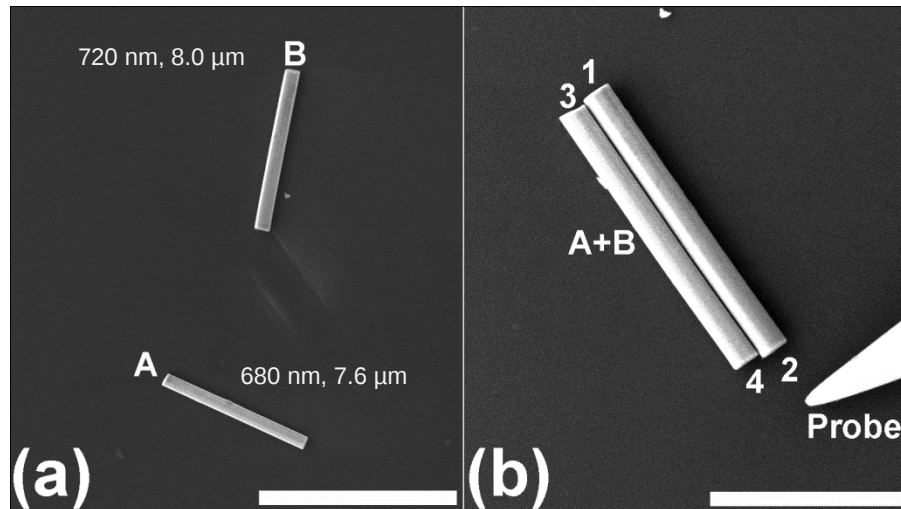
Q. Li et al., *Opt. Exp.* **20** 17873 (2012)

Single-mode: Narrow linewidth ($< 0.1\text{ nm}$), $\sim 150\text{ dB}$ Side Mode Suppression Ratio, and **Low Threshold** ($\sim 250\text{ kW/cm}^2$)

Reducing the dimensionality of the wire ($< \sim 130\text{ nm}$ diameter and $< \sim 6\text{ }\mu\text{m}$ length) lowers the number of competing modes, leading to single-mode lasing.



Method 2: Single-mode lasing via coupled nanowire cavities

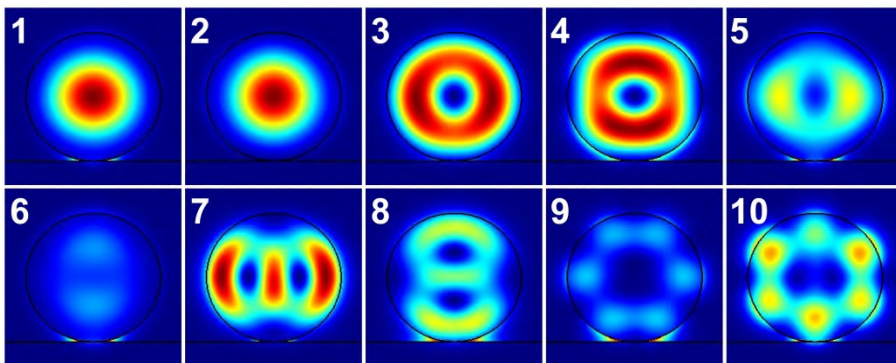
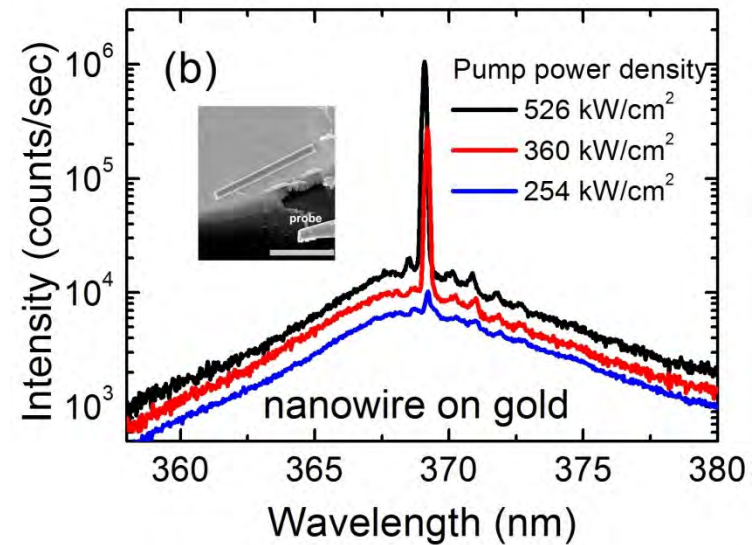
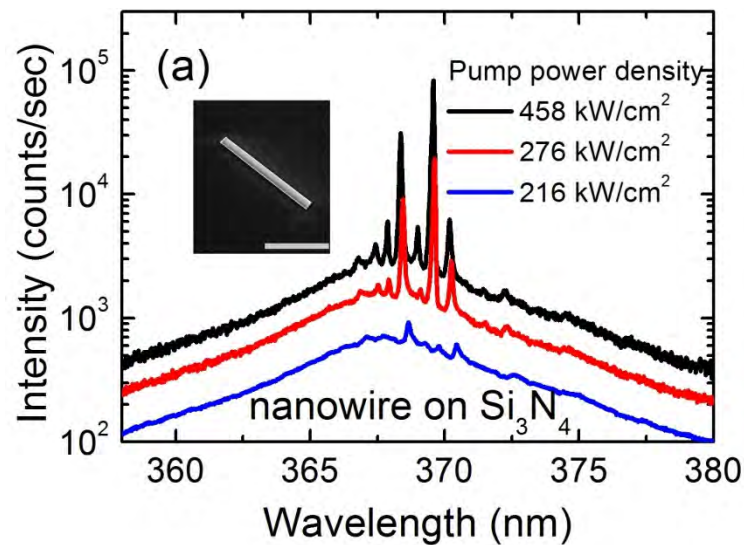


- GaN NWs need to be $\leq \sim 130$ nm for single transverse mode behavior; larger single-mode NWs?
- Individual large NWs shows multiple modes.
- Coupled nanowires show single mode!
- Vernier effect – only resonant modes survive

modeling: Huiwen Xu (UNM)

H. Xu et al., *Appl. Phys. Lett.* **101** 113106 (2012)

Method 3: Metal substrate induced single-mode nanowire lasing



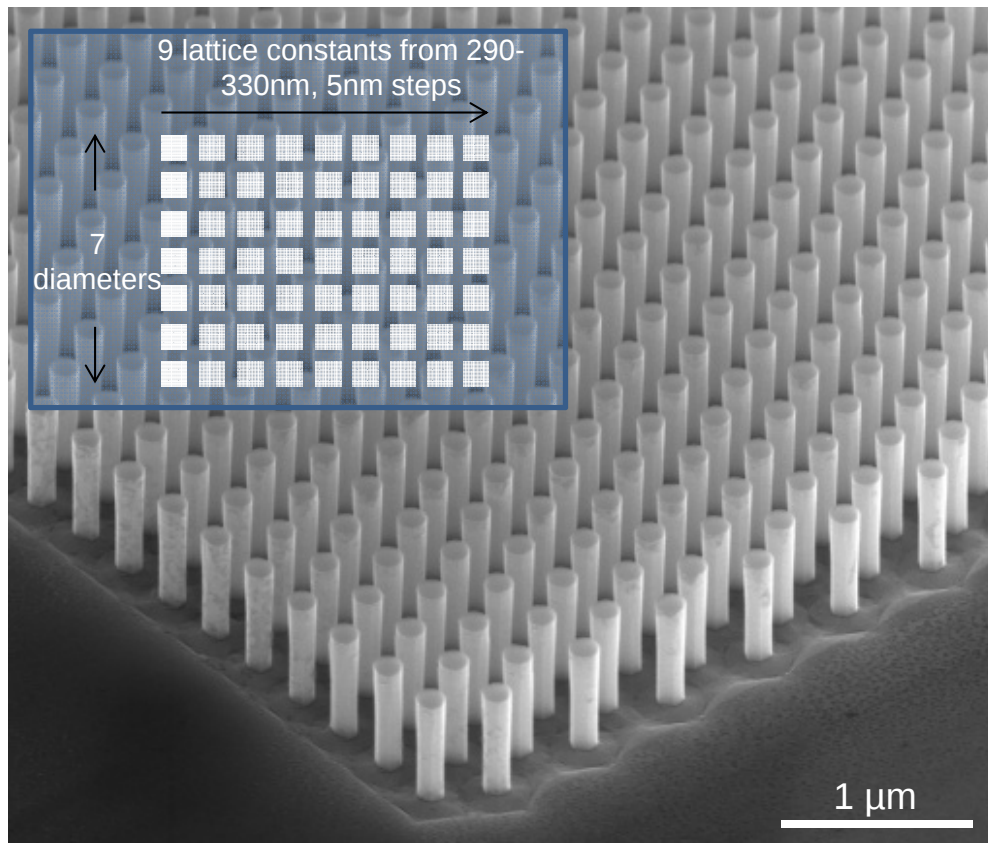
- NWs on Si_3N_4 show multi-mode lasing
- Same NWs moved onto gold-coated spot show single-mode lasing!
- Metal substrate induces mode-dependent loss mechanism

H. Xu et al., *Appl. Phys. Lett.* **101** 221114 (2012)

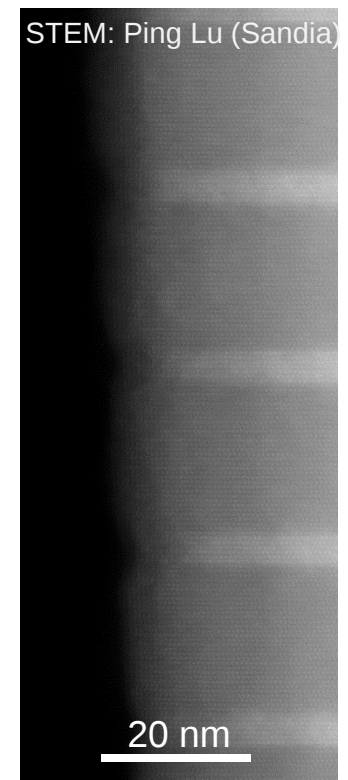
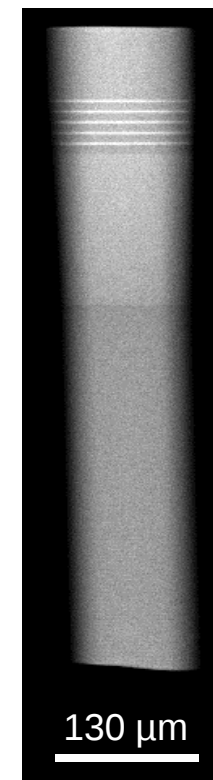


III-N Nanowire Photonic Crystal (PC) Lasers

Motivation: Achieve single-mode, tunable lasing on same chip. Applications in optical information processing, biology, solid state lighting, displays, etc.



Nanowire PCs fabricated by top-down method using e-beam lithographic mask



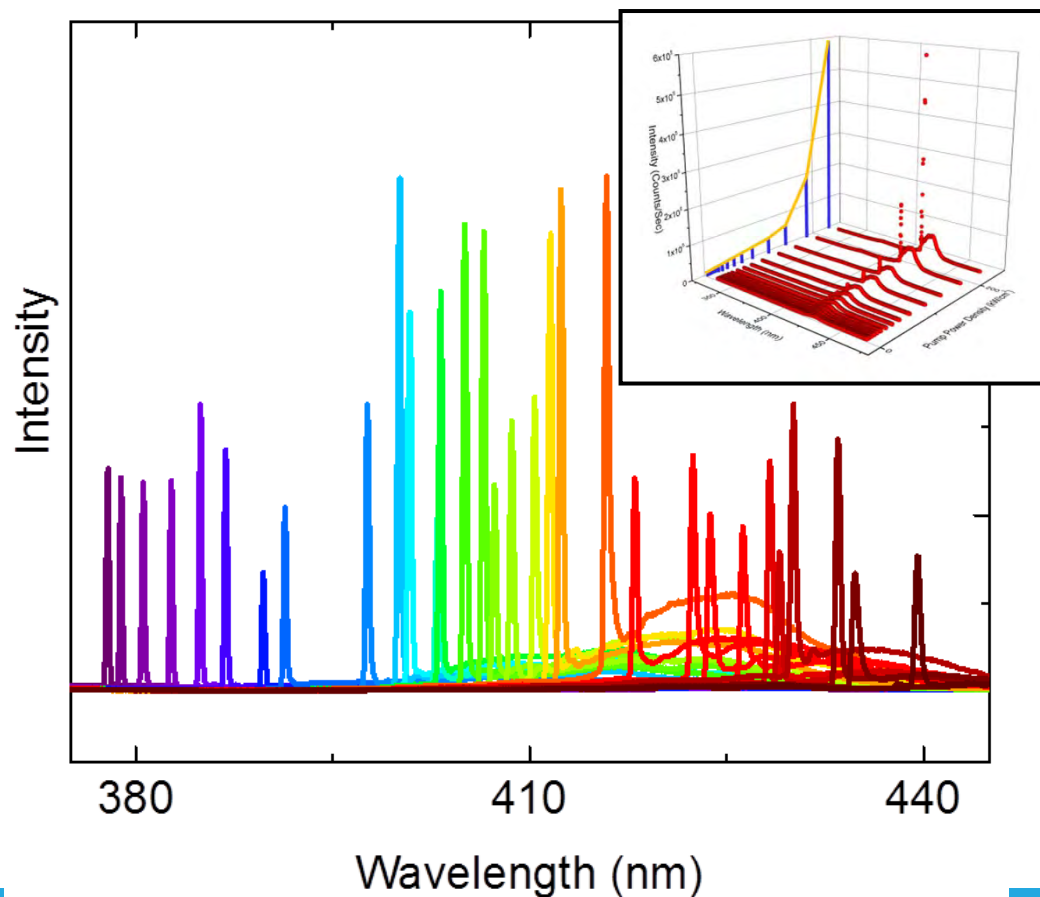
NW STEM images: 5x MQW InGaN emission centered at 420nm, $\text{In}_{0.02}\text{GaN}$ underlayer



III-N Nanowire Photonic Crystal Lasers

Broad gain width of InGaN MQWs with PC design allows for tunable single mode lasing over large range on same chip

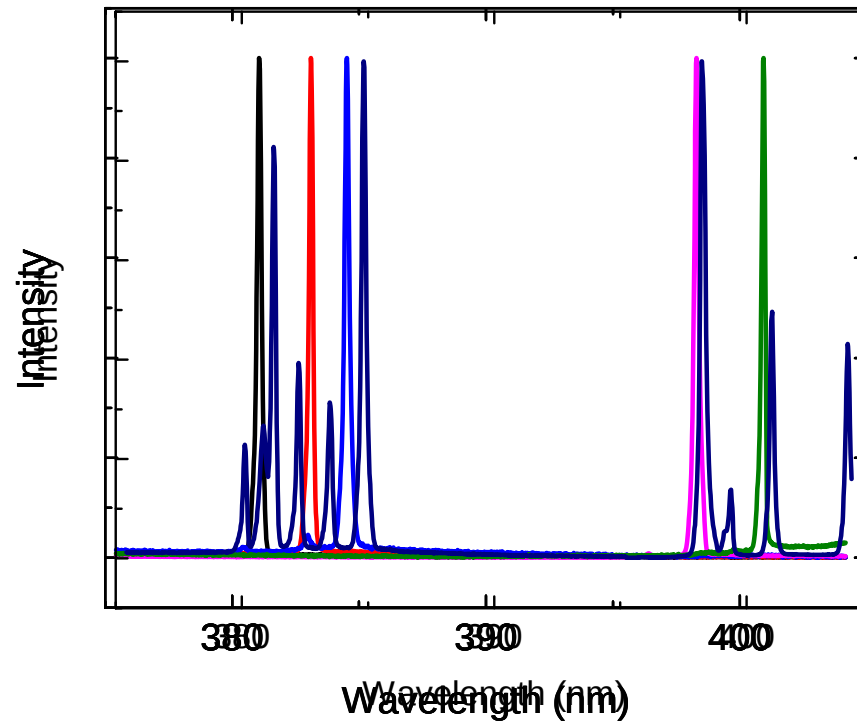
61 color nanowire laser array



- High-yield >95% (2 of the PCLs were accidentally removed during sample handling.)
- Spectral Coverage from 380-440nm.
- Emission wavelength increases with the diameter and the lattice constant
- Thresholds are reasonable compared to other optically pumped III-N nanowire devices. (<500kW/cm² for all devices)



III-N Nanowire Photonic Crystal Lasers



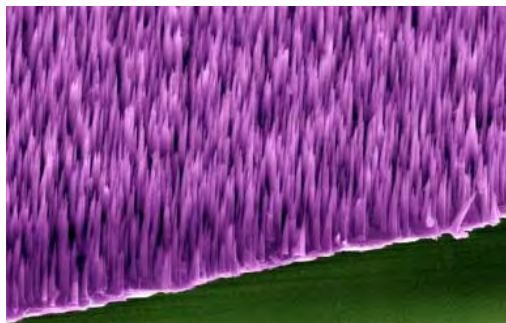
pitch: 320 nm
diameter: 130-140nm





Summary - Bottom-up III-nitride nanowires

Vertically-aligned growth



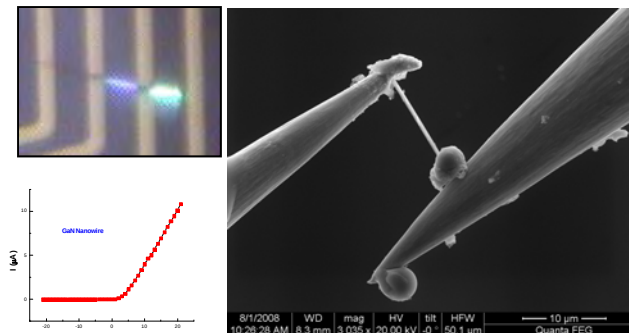
G. T. Wang et al., *Nanotechnology* 17 5773-5780 (2006)
Q. Li, G. T. Wang, *Appl. Phys. Lett.* 93, 043119 (2008)
Q. Li, J. R. Creighton, G.T. Wang, *J. Crys. Growth* 310 3706-3709 (2008)

Nanowire-templated growth



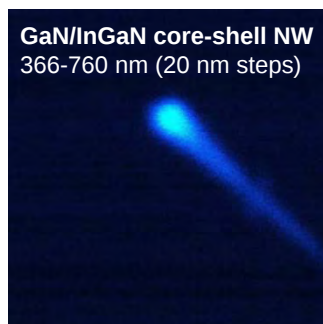
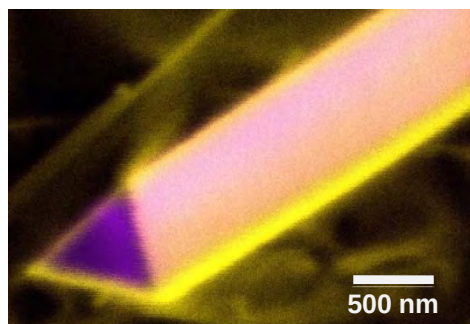
Q. Li, Y. Lin, J.R. Creighton, J. Figiel, G.T. Wang, *Adv. Mat.*, 21 2416-2420 (2009)

Electrical characterization



A. A. Talin, G. T. Wang, E. Lai, R. J. Anderson, *Appl. Phys. Lett.* 92 093105 (2008)
Y. Lin, Q. Li, A. Armstrong, and G. T. Wang, *Solid State Commun.*, 149, 1608 (2009)

Optical imaging and spectroscopy



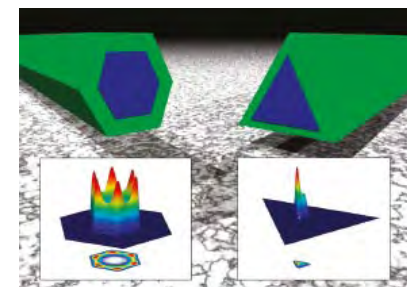
Q. Li, G. T. Wang, *Nano Lett.*, 2010, 10 (5), 1554 [GaN defect CL]
Q. M. Li, G. T. Wang, "*Appl. Phys. Lett.*", 97, 181107, 2010. [GaN/InGaN]
P.C. Uppadhya et al. *Semicond. Sci. Tech.* 25 024017 (2010) [Ultrafast]
A. Armstrong, Q. Li, Y. Lin, A. A. Talin, G. T. Wang, *APL* 96, 163106 (2010). [DLOS]

In-situ TEM



T. Westover et al., *Nano Lett.*, 9, 257 (2009). [in-situ NW breakdown]
J. Y. Huang et al., *Nano Lett.*, 11 (4), 1618 (2011). [in-situ nanomechanics]

Theory

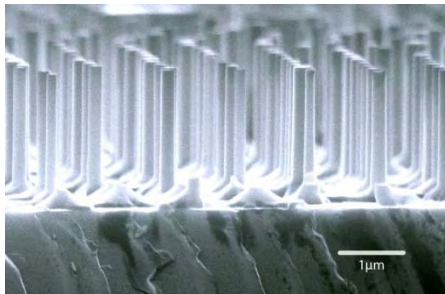


B. Wong et al., *Nano Lett* 11 (8), 3074, 2011

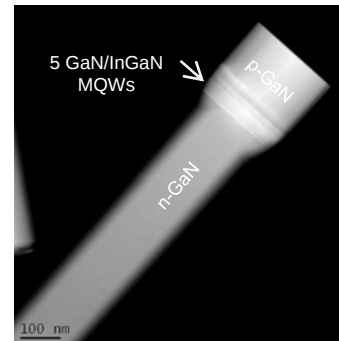


Summary – Top-down III-nitride nanowires

Top-down fabrication

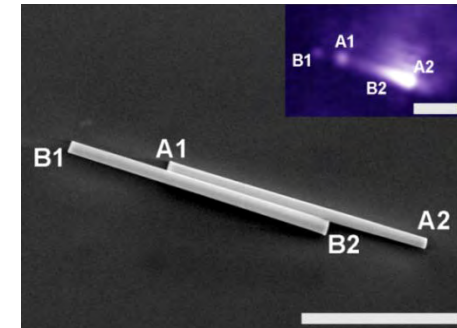


Nanowire LED “flashlight”



Q. Li et al., *Optics Express* **19**, 25528 (2011)

Single-mode GaN nanowire lasers

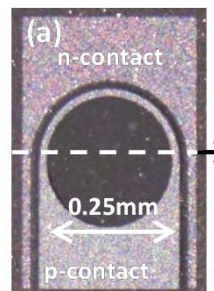
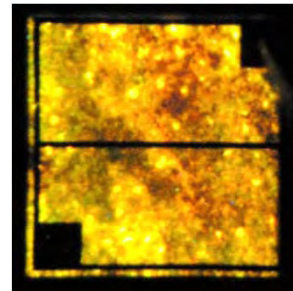
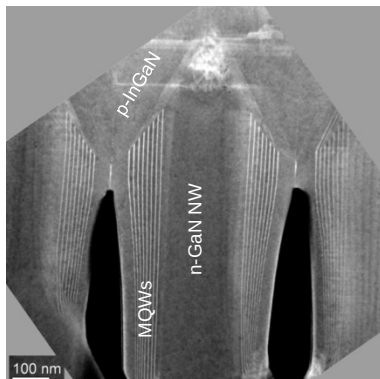


Q. Li et al., *Optics Express* **20** 17874 (2012)

H. Xu et al., *Appl. Phys. Lett.* **101** 113106 (2012)

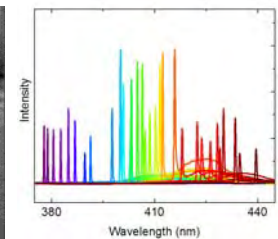
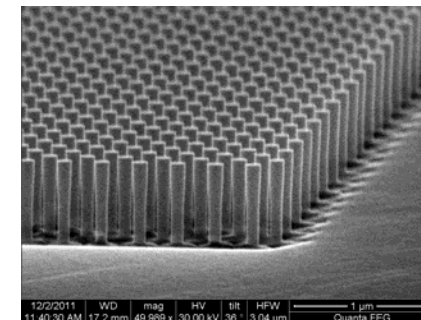
H. Xu et al., *Appl. Phys. Lett.* **101** 221114 (2012)

Vertically integrated radial nanowire LEDs and solar cells



J. Wierer et al., *Nanotechnology* **23** 194007 (2012)

Tunable nanowire photonic crystal lasers



J.B. Wright et al., *in preparation*

Summary

- **III-nitride nanowire based architectures have several potential advantages over planar-based devices for solid-state lighting, but numerous scientific & technical challenges in fabrication, performance, device contacts**
- **Sandia research highlights**
 - **Growth and properties of bottom-up III-nitride nanowires**
 - **New top-down (+ regrowth) fabrication for controlled geometries, flexible design, high quality, easier vertical device integration**
 - **Top-down nanowire LEDs, solar cells, lasers**

Acknowledgments

Qiming Li - nanowire growth, nano-CL, TEM/EDXS, nanofabrication, strain-modeling

Jeffrey Figiel, Randy Creighton, Karen Cross –MOCVD growth, device processing & support

Jianyu Huang – In-situ SPM-TEM for correlated structure-property studies

Jonathan Wierer – LED/solar cell device fabrication/characterization

Karl Westlake, Mary Crawford – PL, IQE measurements

Daniel Koleske – LED growth

Igal Brener, Willie Luk, Weng Chow, **Jeremy Wright, (Ph.D student)**,

Huiwen Xu (Ph. D student), Ganesh Subramania – NW [PC] lasers



Funding Acknowledgment: DOE Basic Energy Sciences (BES) DMSE, Sandia's Solid-State-Lighting Science Energy Frontier Research Center (DOE BES), and Sandia's LDRD program

Contact: e-mail: gtwang@sandia.gov

<http://www.sandia.gov/~gtwang>

George T. Wang

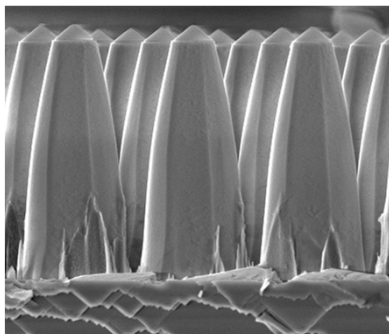




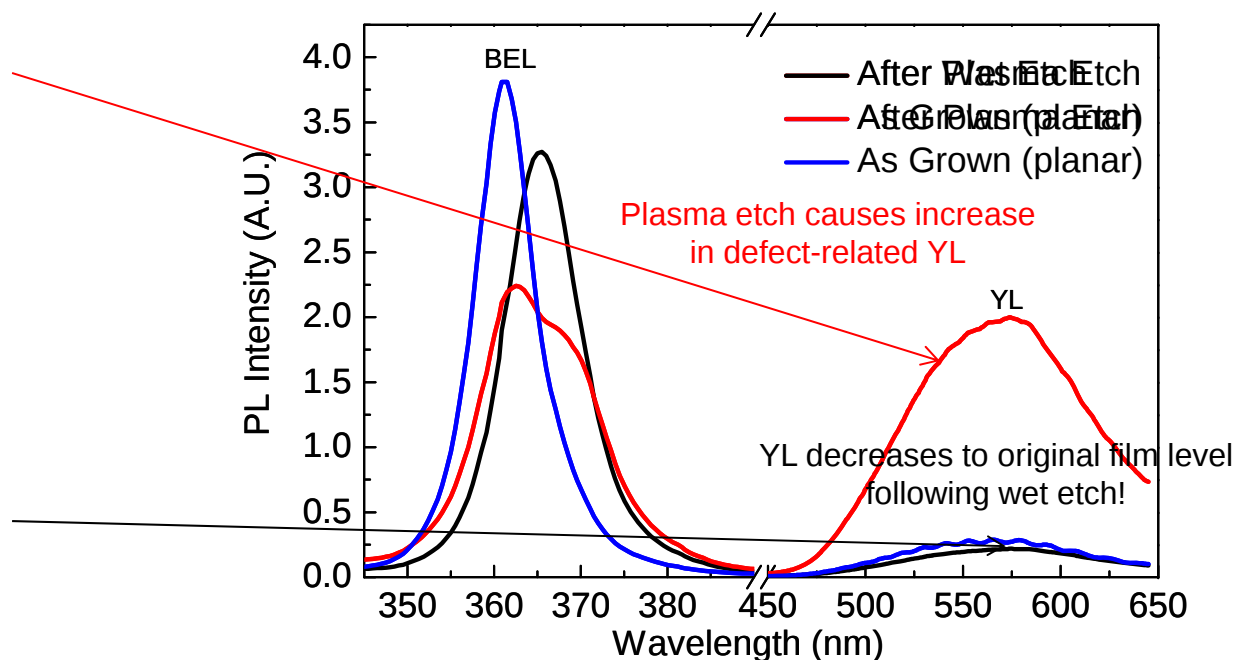
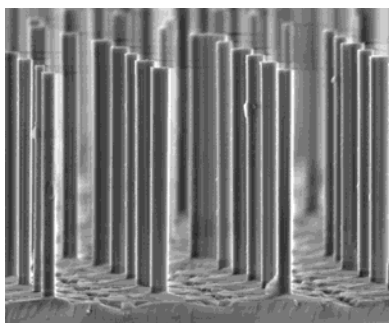
Backup/Extra Slides

Wet etch step removes plasma etch damage

Plasma etch only



After wet etch



Lasers for Solid State Lighting

Advantages of lasers for lighting:

- Lasers show very high efficiency at high power
- LED and LD current densities are converging
- Carrier density is clamped at threshold
 - Circumvent the droop problem in LEDs
 - Need to reduce threshold to avoid losses
- After threshold slope efficiency is one
- Directionality, polarized emission, modulation

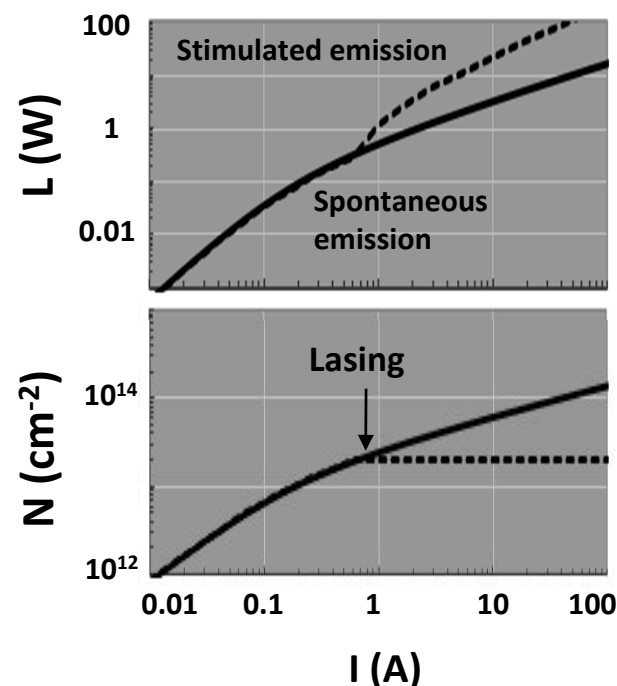


Randy Montoya, Sandia

Laser Sources For SSL:

- High efficiency
- Low threshold
- Focus on III-nitrides
- **Nanowire lasers**
 - Low threshold
- **Polariton lasers**
 - Ultralow threshold
 - New physics

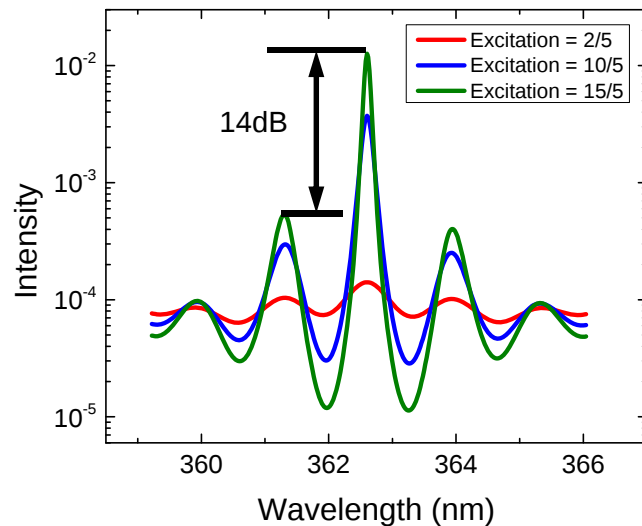
Clamped carrier density



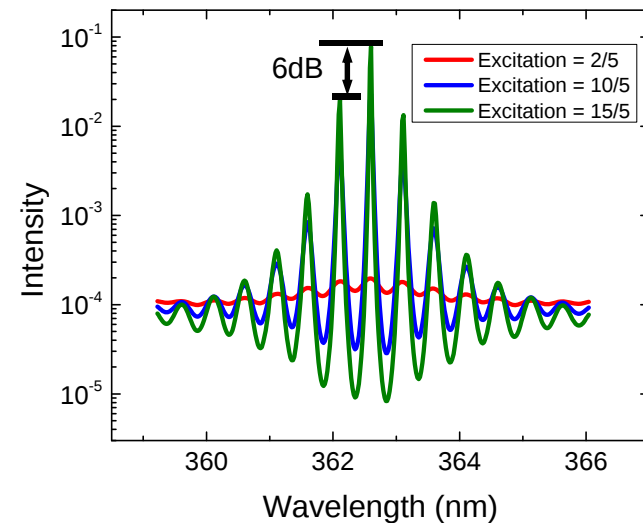
Are narrow linewidth sources acceptable?

Single mode GaN nanowire laser

4 μm long, 140 nm dia. nanowire



12 μm long, 140 nm dia. wire



- Multimode laser theory calculations to determine which of the passive-cavity eigenmodes will be above lasing threshold for given experimental conditions.
- Modeling shows that by reducing the dimensionality of the wire we can reduce the number of competing modes, leading to single-mode lasing.



Outline

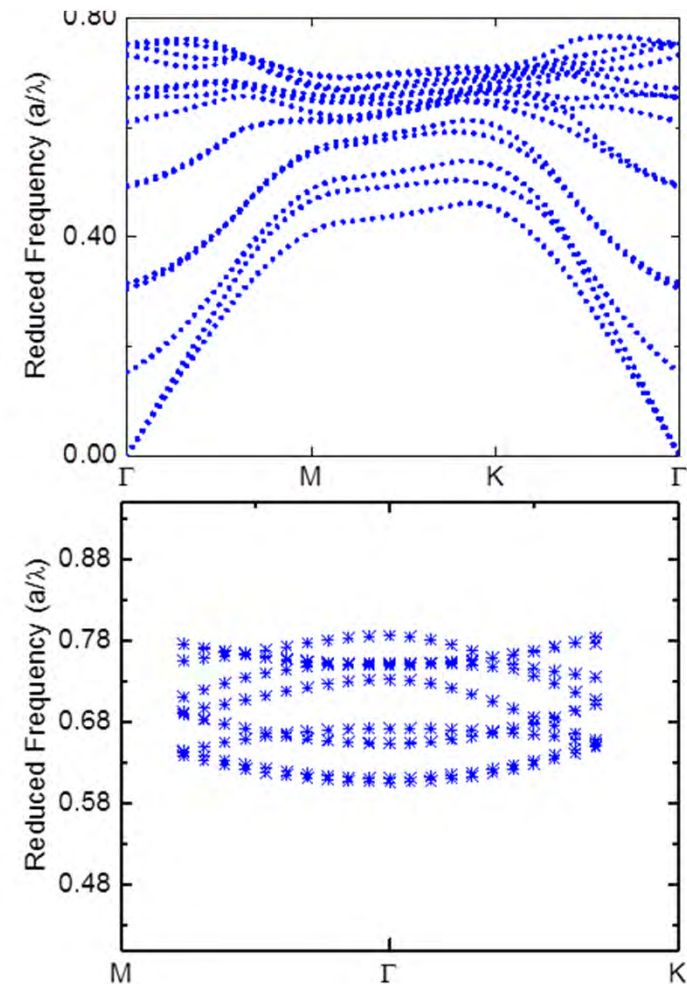
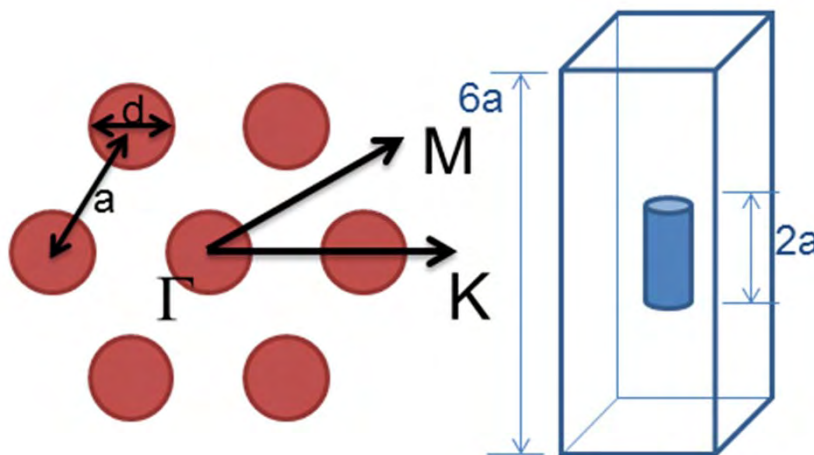
- **Why III-nitride nanowires for solid-state lighting, PV, etc. ?**
- **Bottom-up nanowires**
 - **Growth, characterization, nanowire-templated film growth**
- **Top-down nanowires**
 - **Fabrication, axial and radial LEDs, solar cell, lasers**
- **Summary**





Design Rationale

- Higher order bands have low dispersion
- We desire low group velocity to enhance the light matter interaction and the formation of standing waves within the gain medium, to allow low lasing thresholds in materials that exhibit reduced gain over larger bandwidth





III-N Nanowire Photonic Crystal Lasers

Continuously tuned photonic crystal stripe

